

図 1 100 制御回路

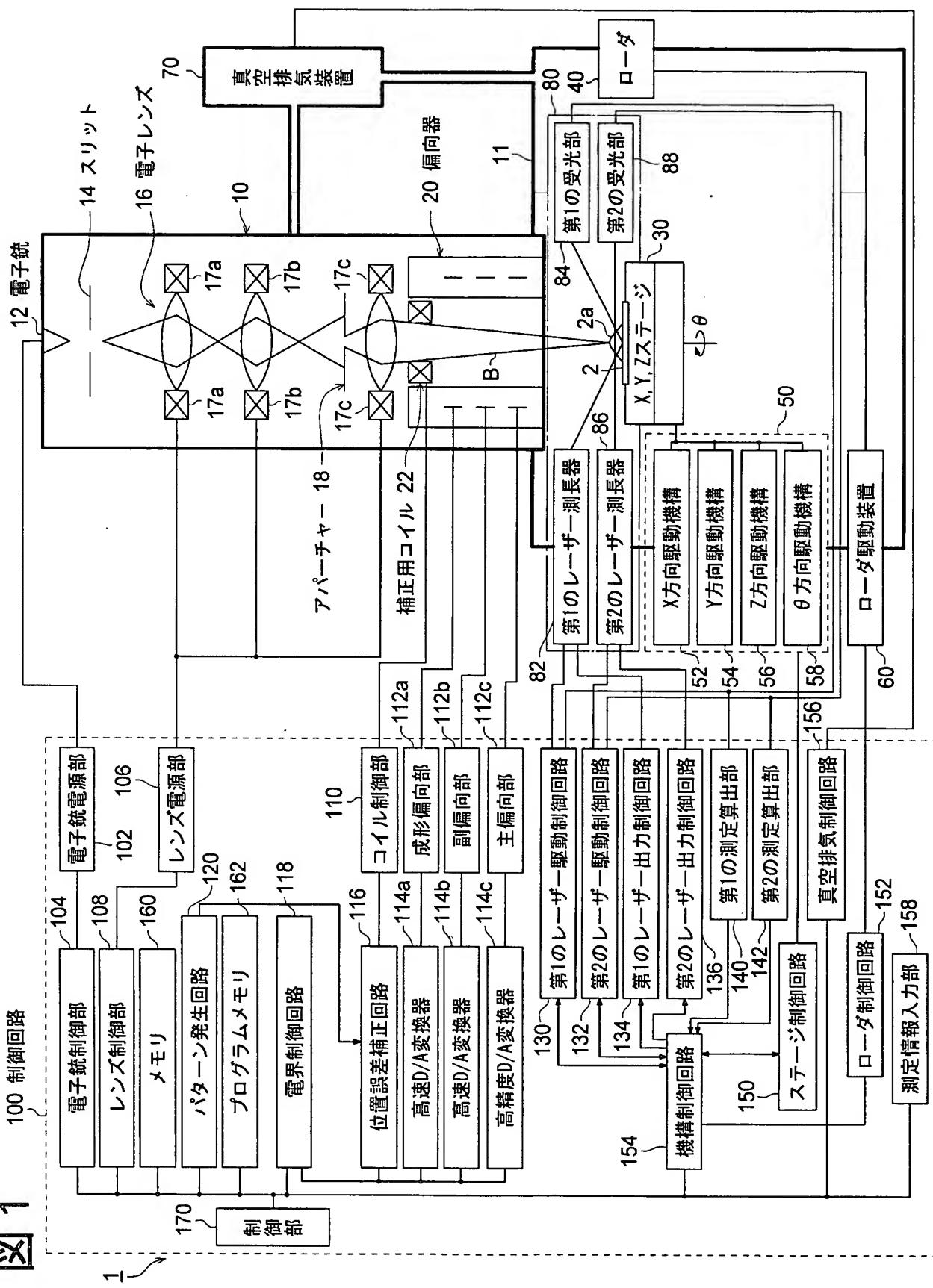


図 2 (A)

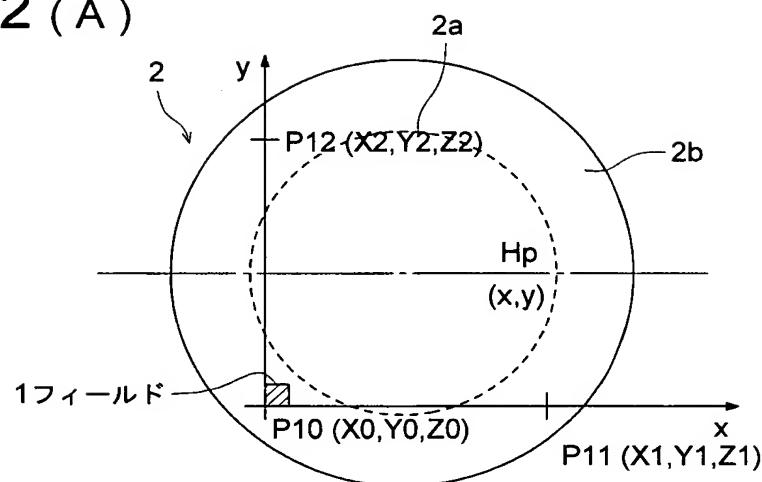


図 2 (B)

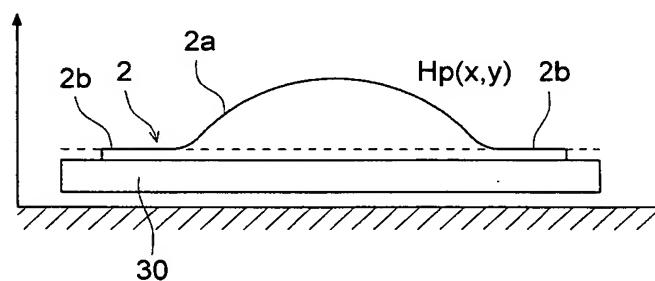


図 2 (C)

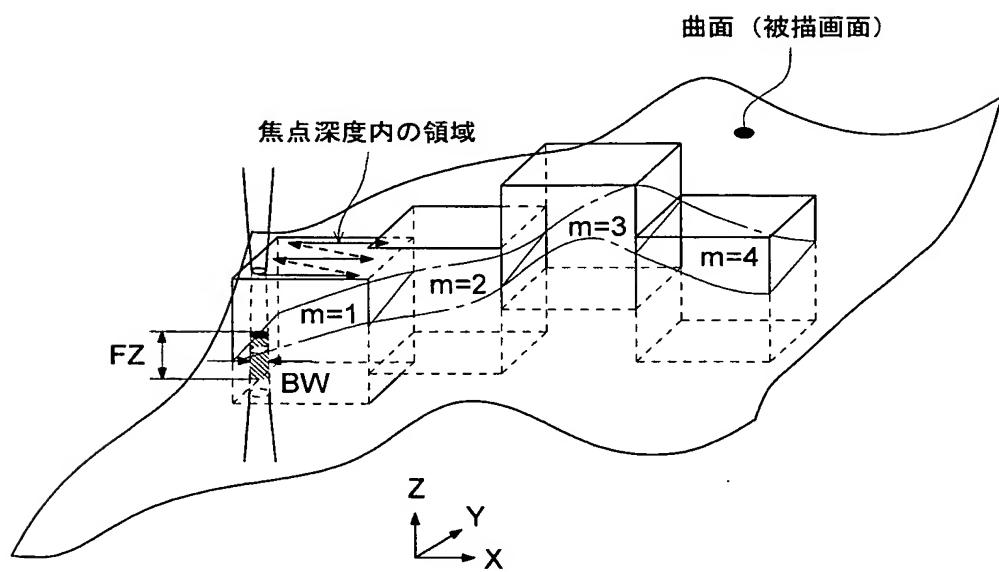


图 3

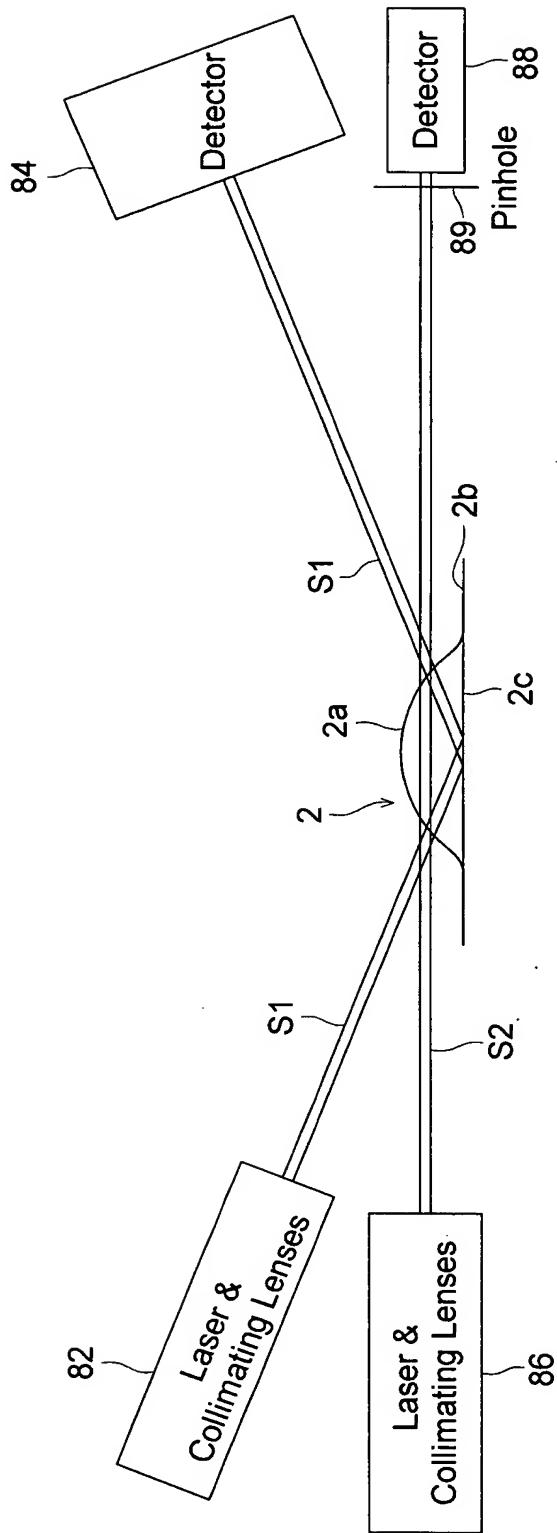


图 4

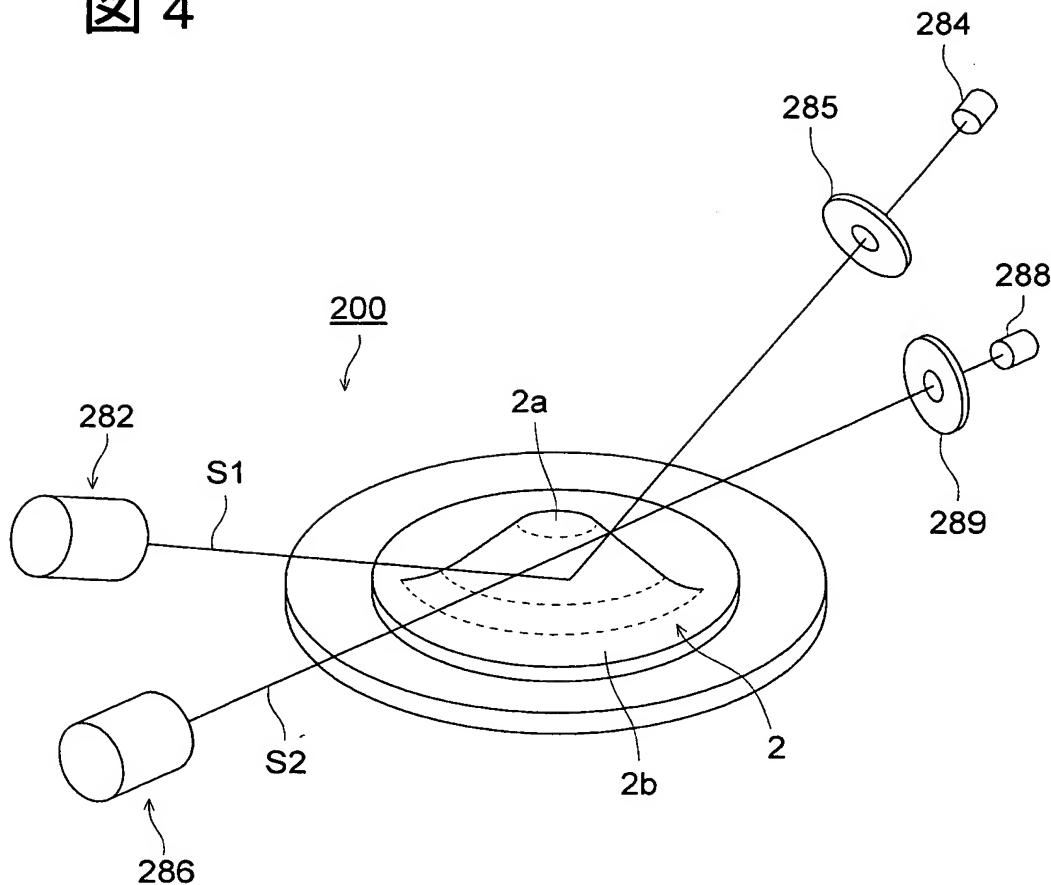


図 5 ( A )

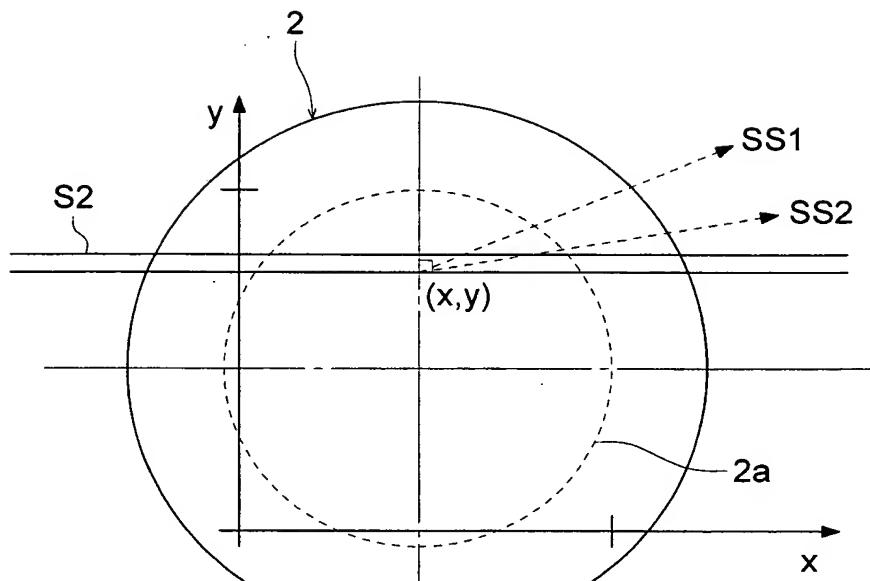


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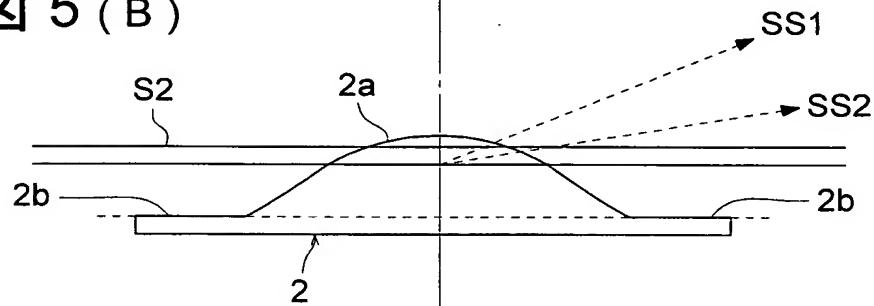


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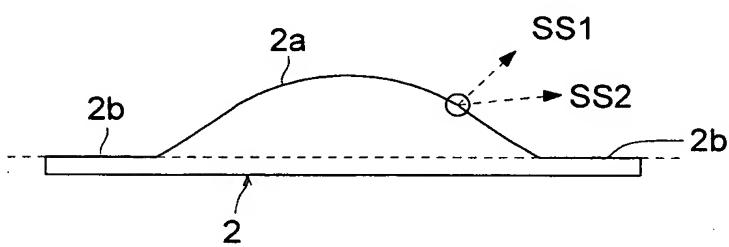


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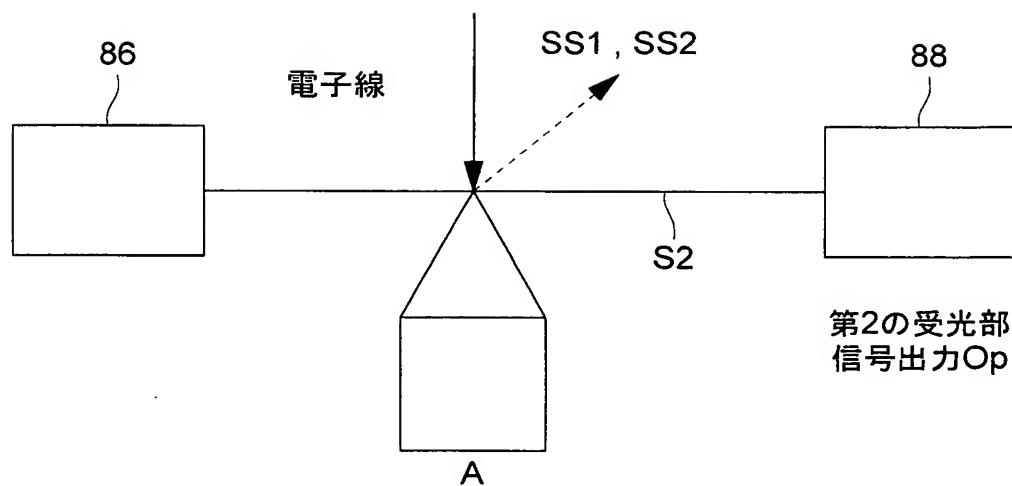


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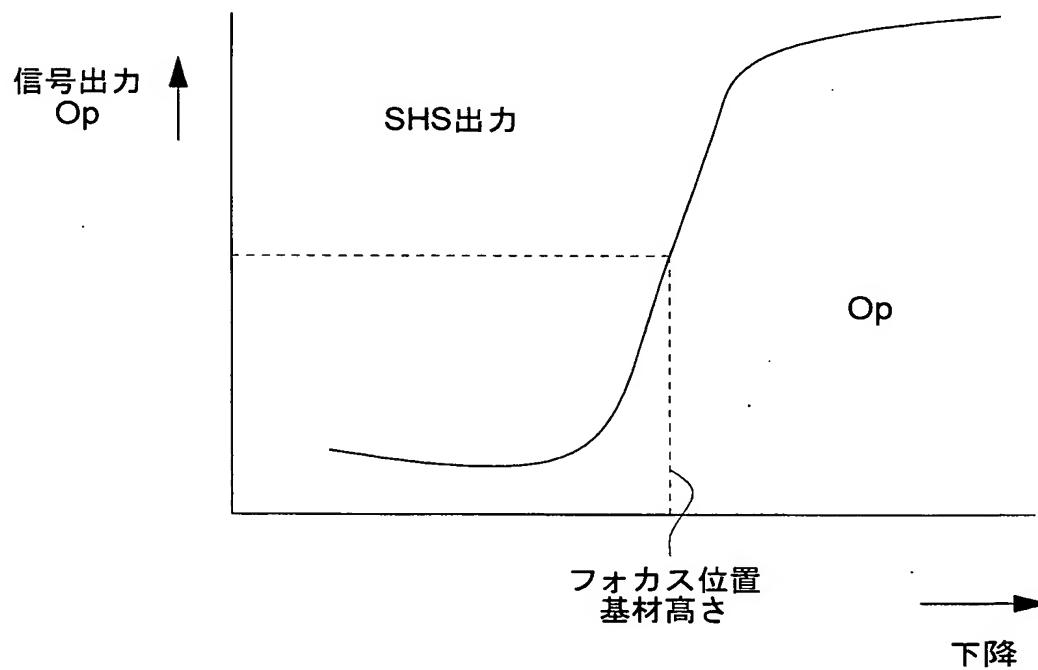


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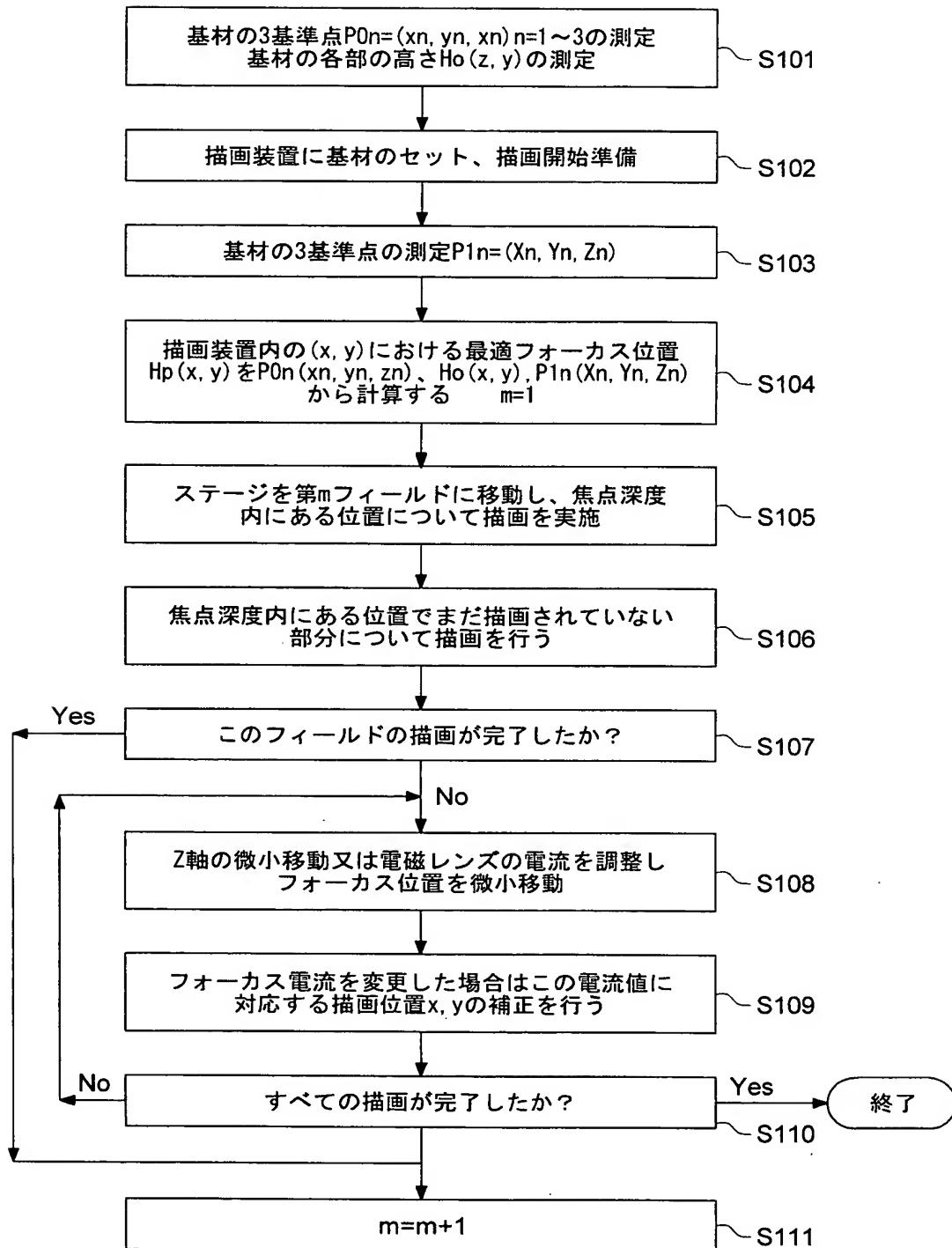
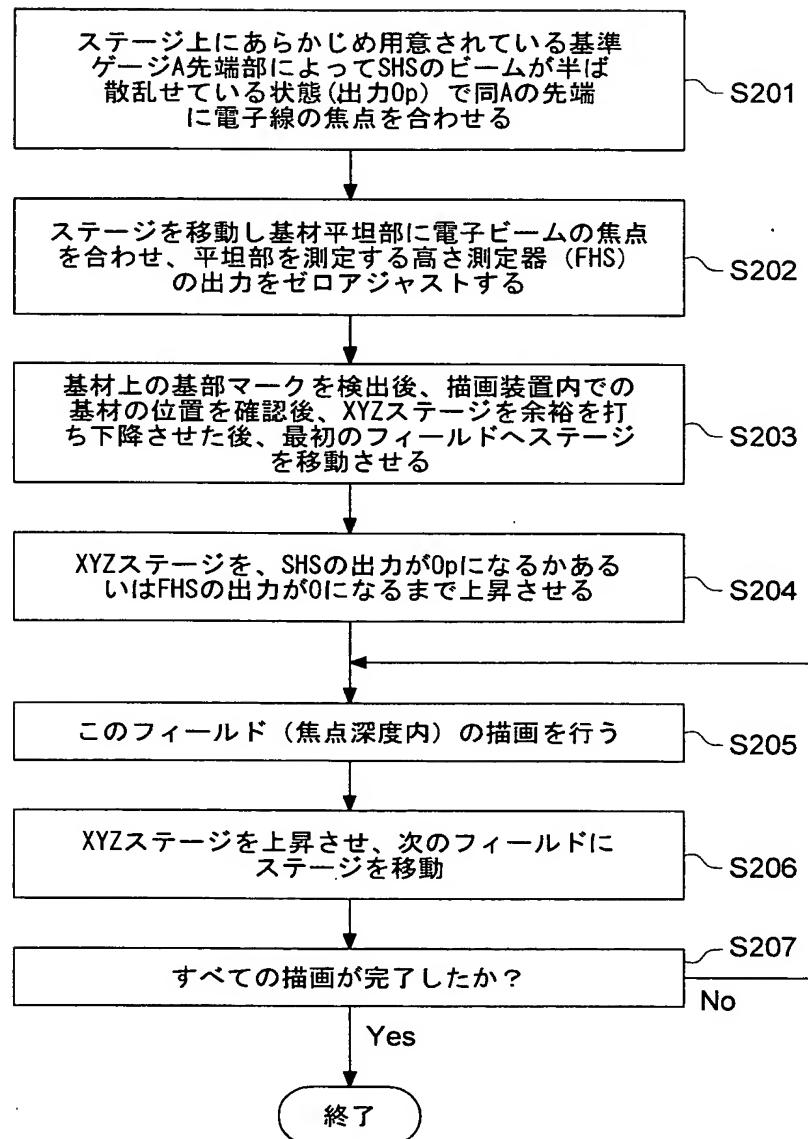
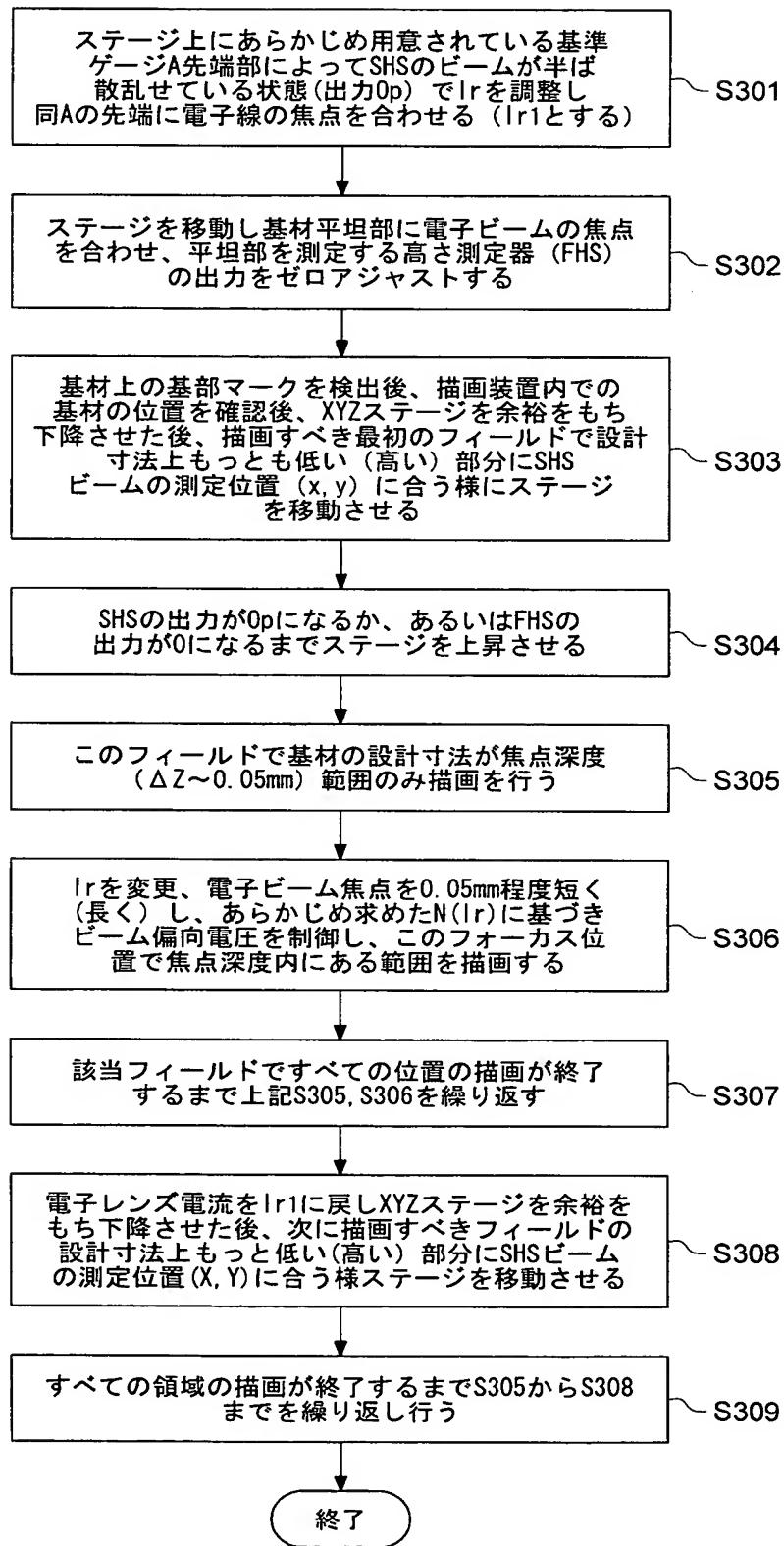


図 9



## 図 10



## 図 11

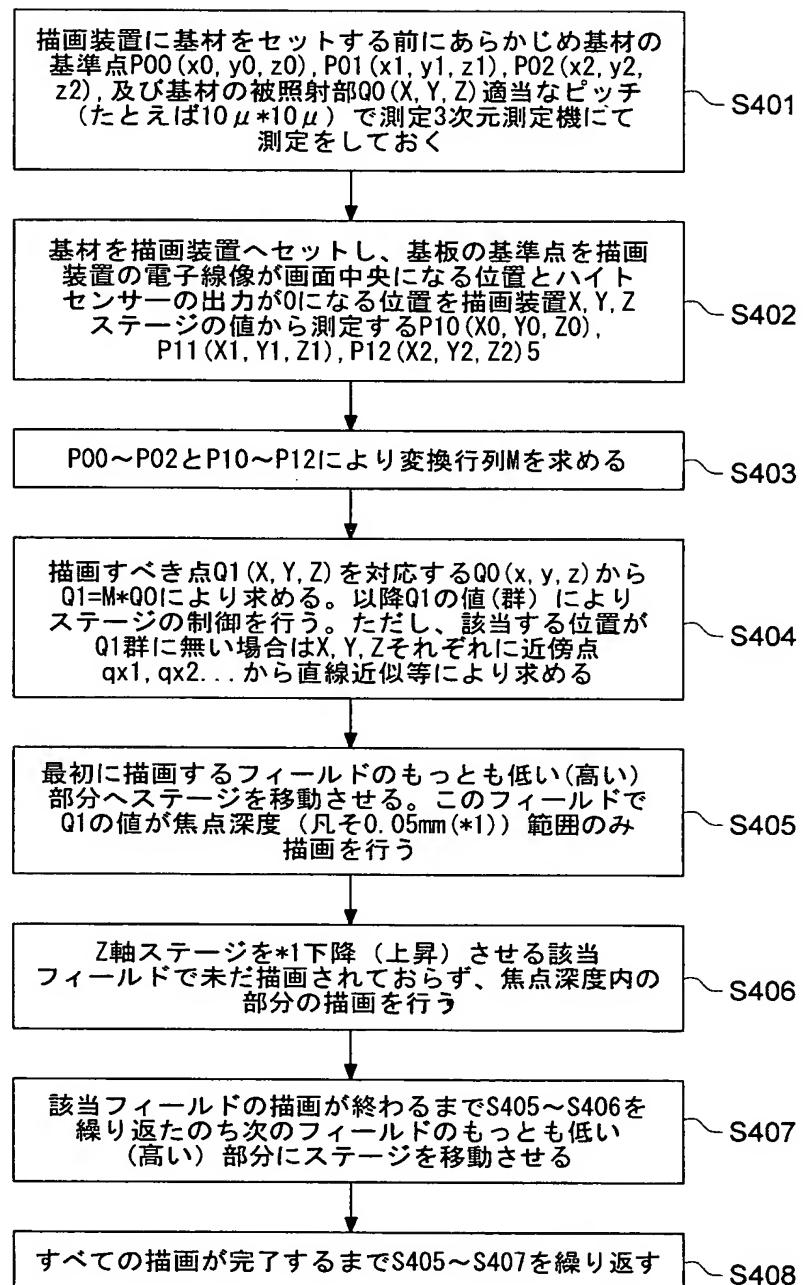
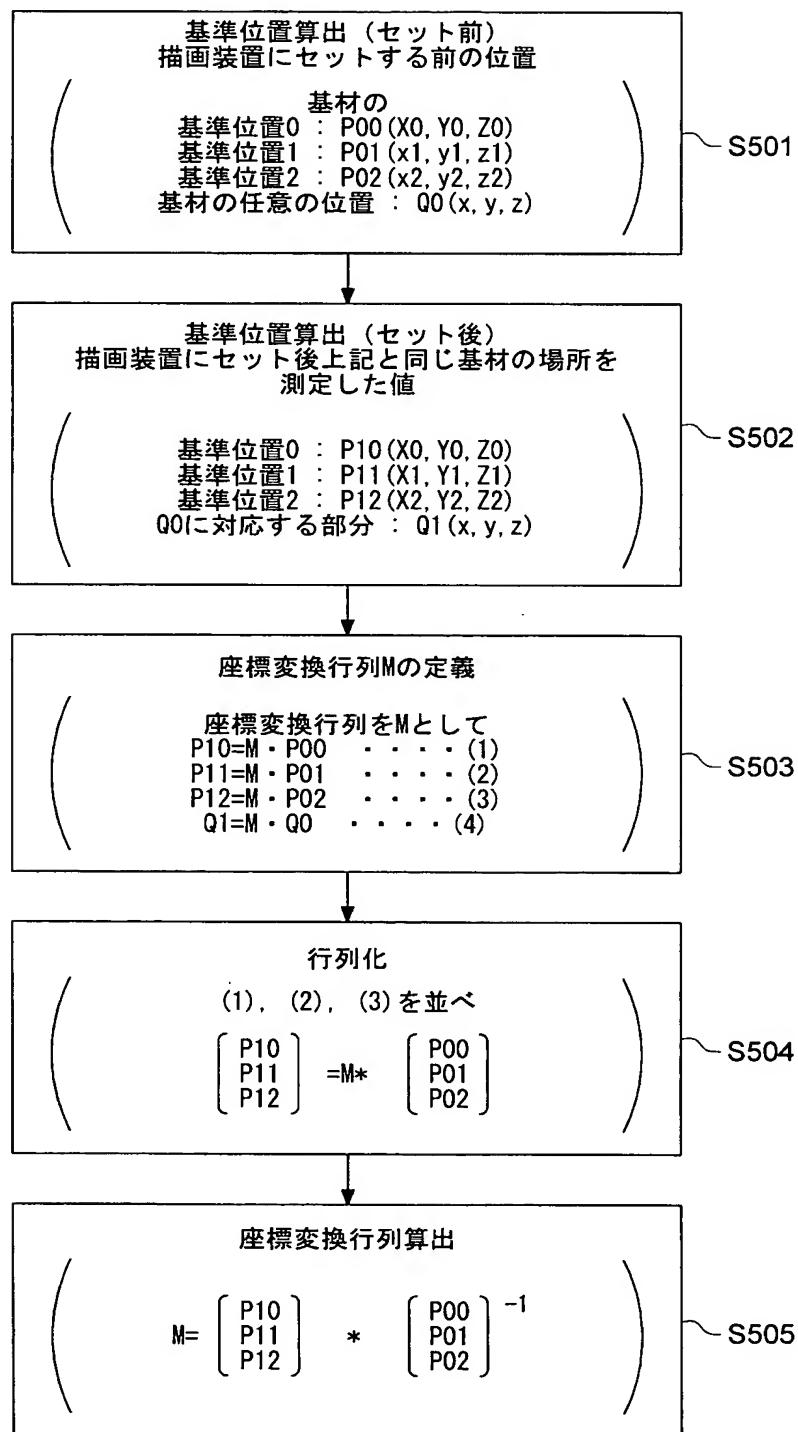
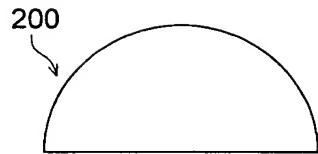


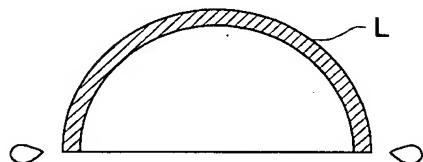
図 12



四 13 (A)



13 (B)



四 13 (c)

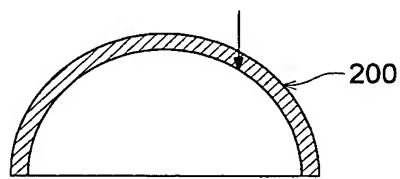


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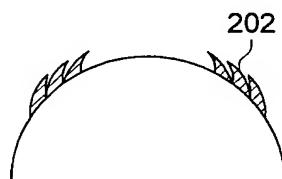


图 13 (E)

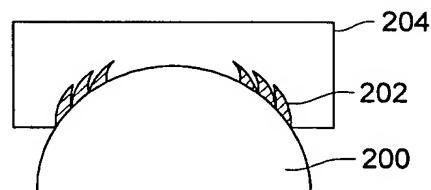


図 13 (F)



図 14

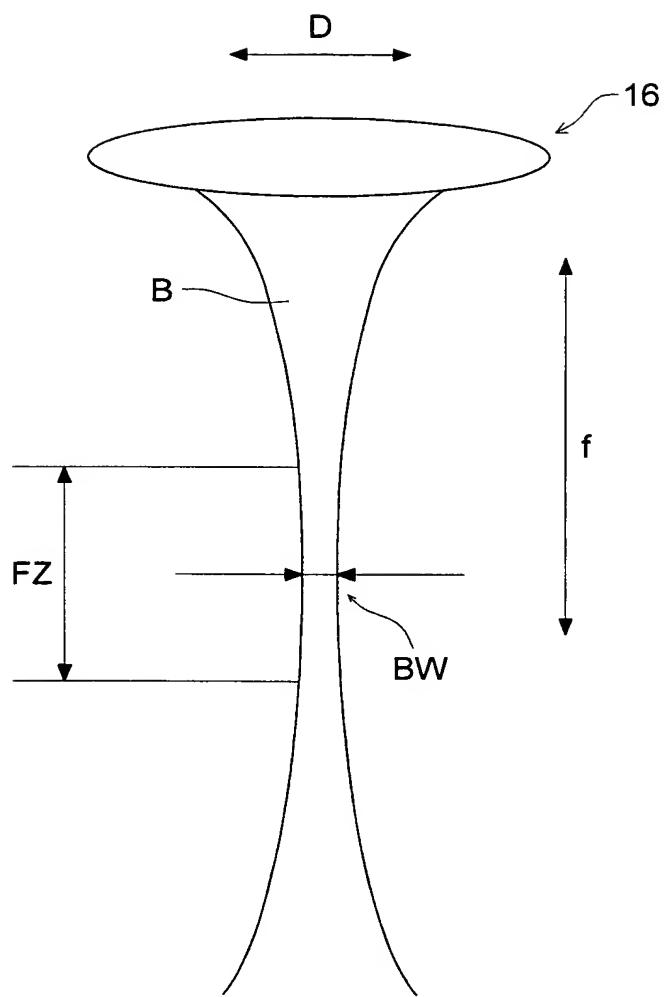


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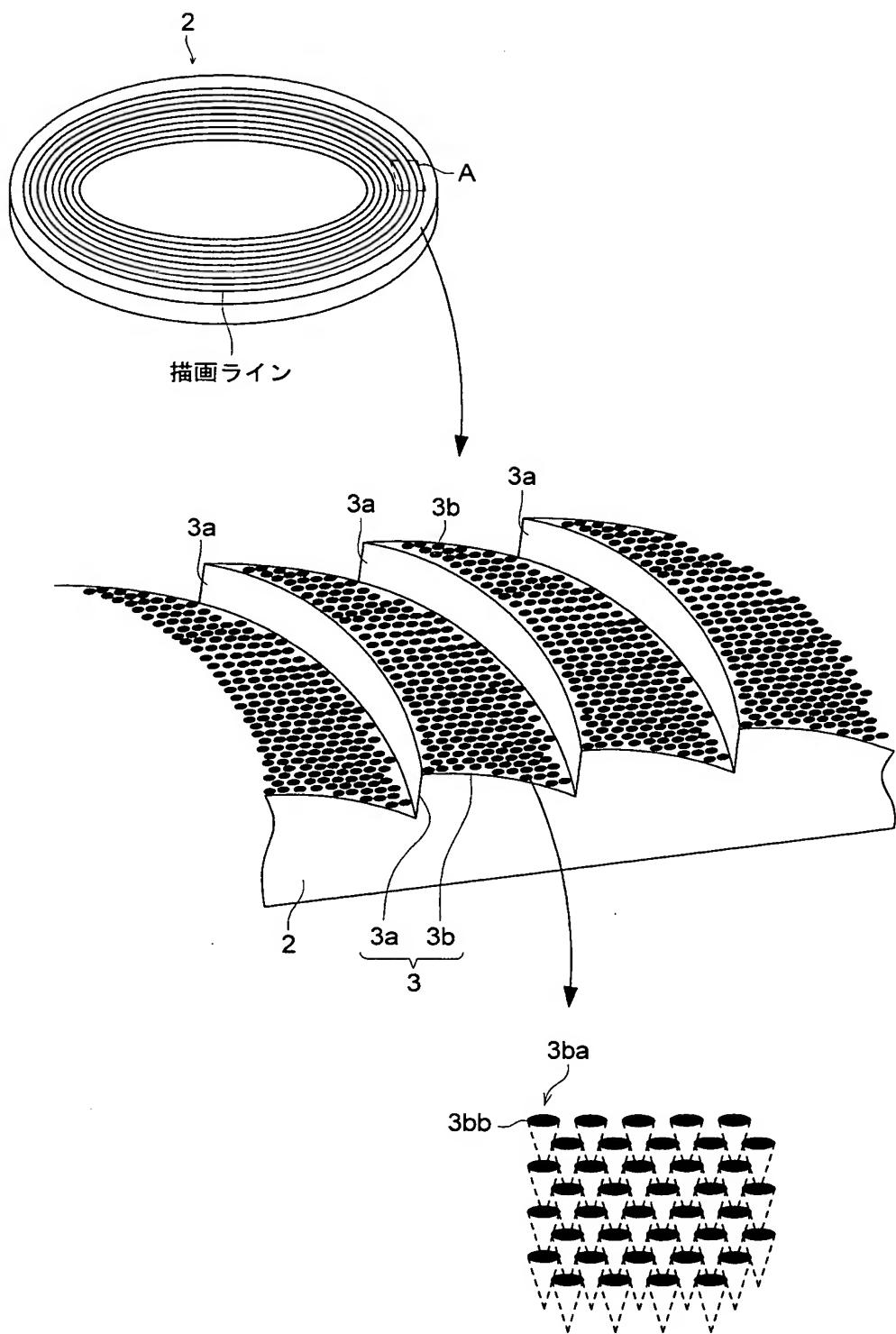


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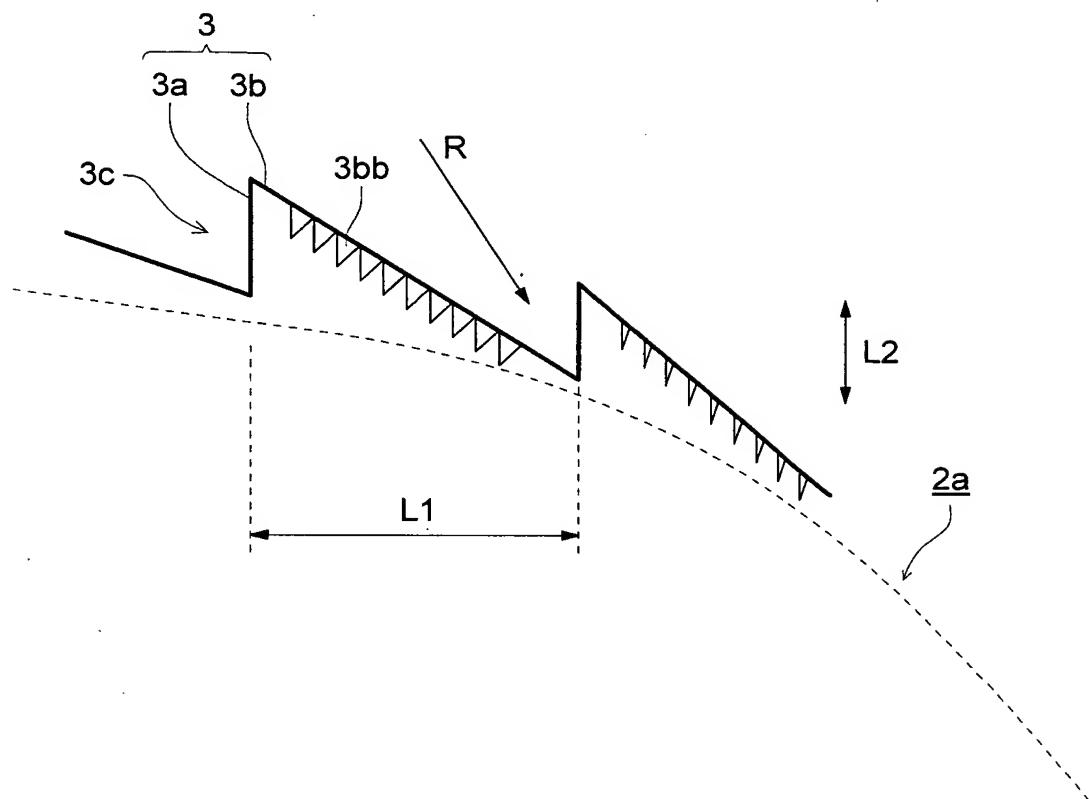


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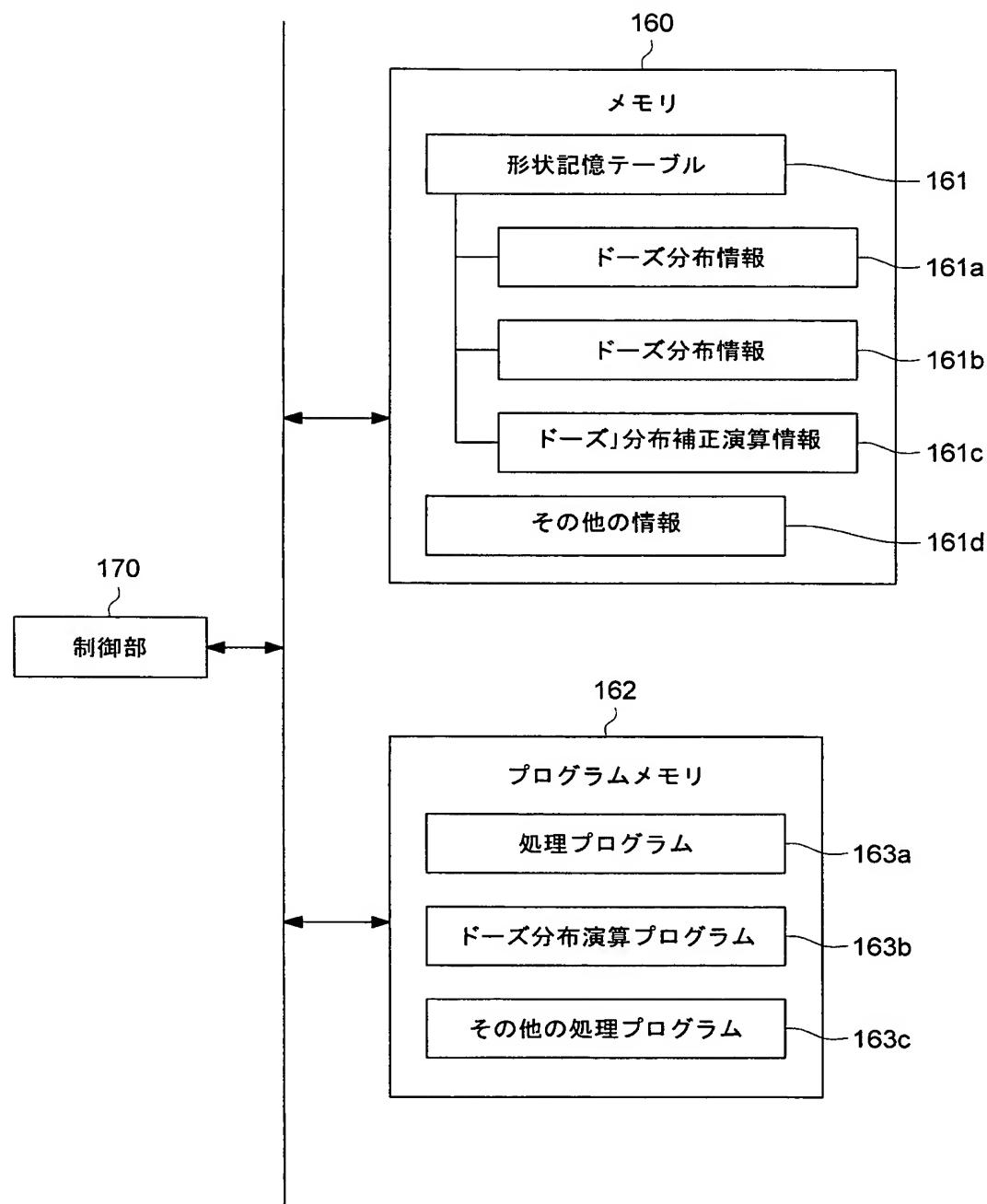


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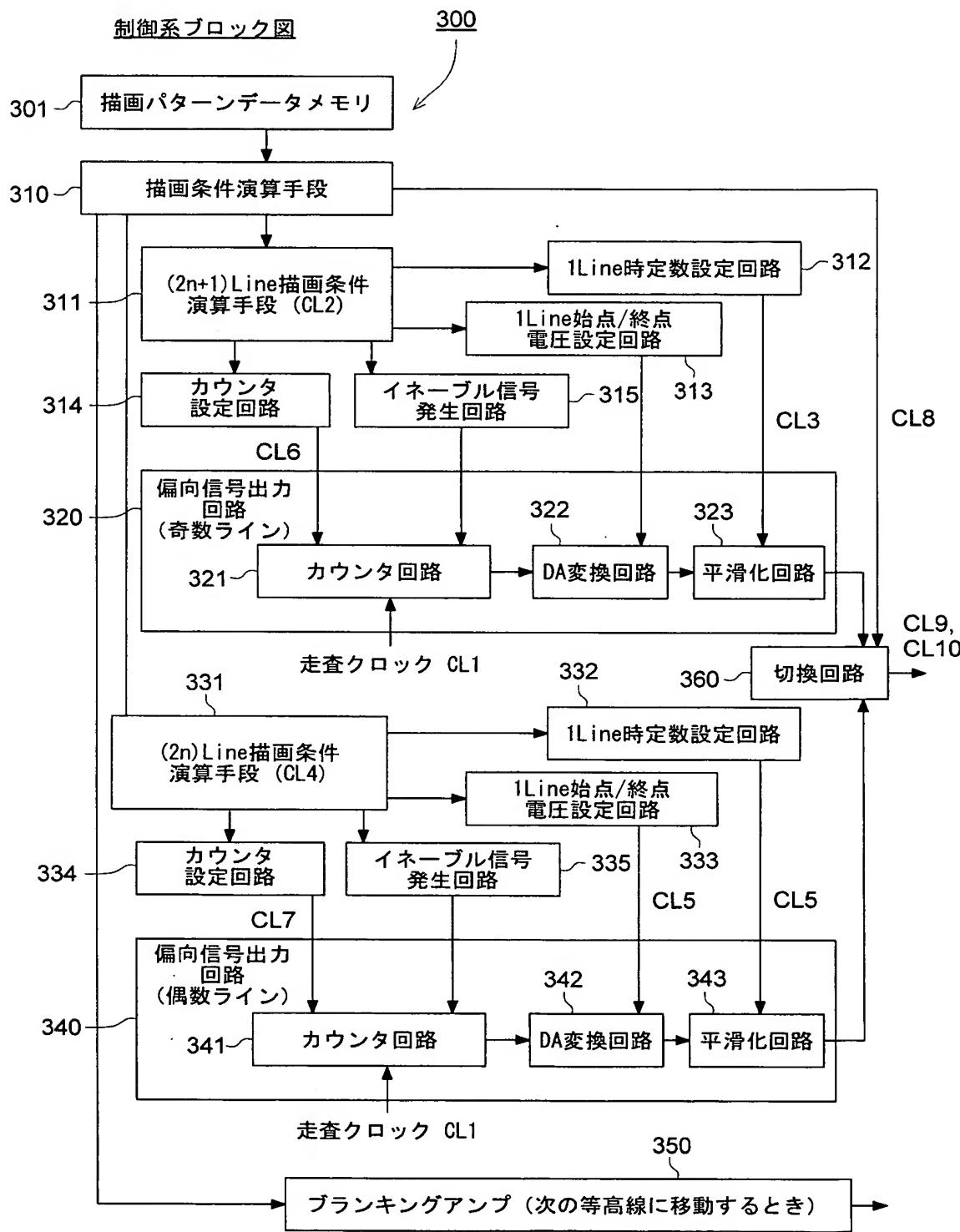


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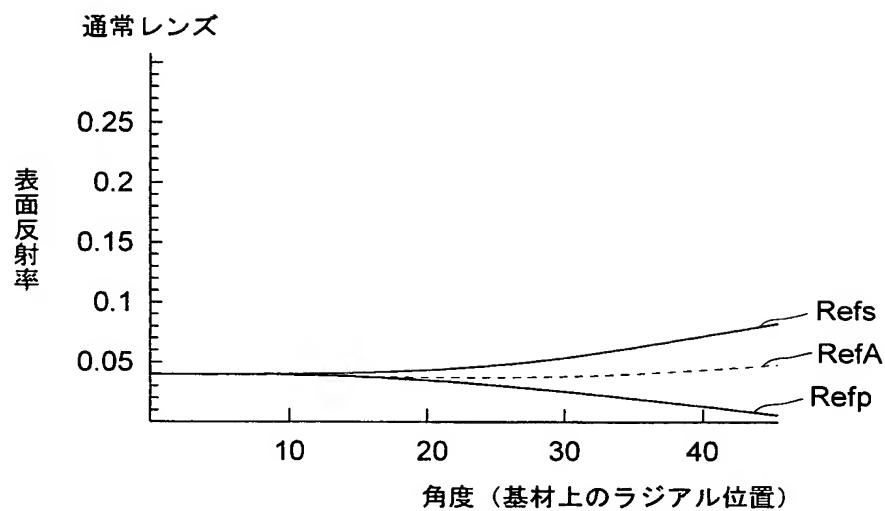


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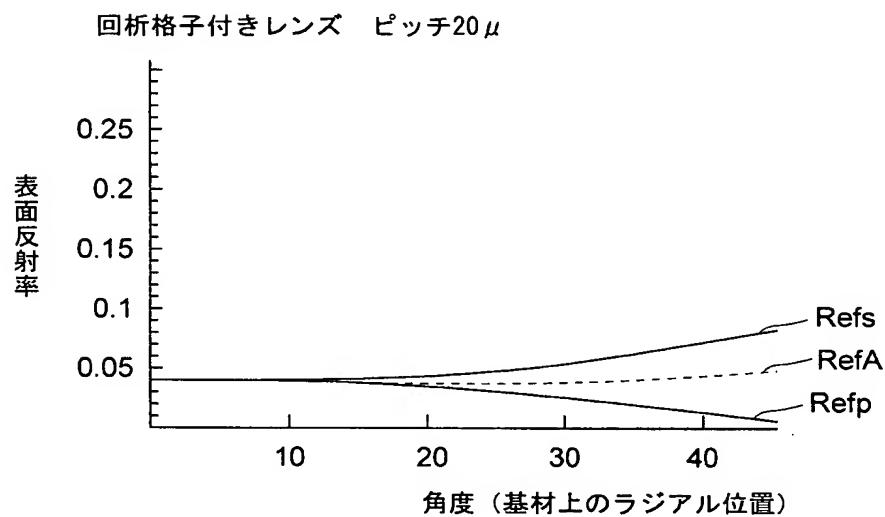


図 21

回析格子のついたレンズ 3ミクロンピッチ

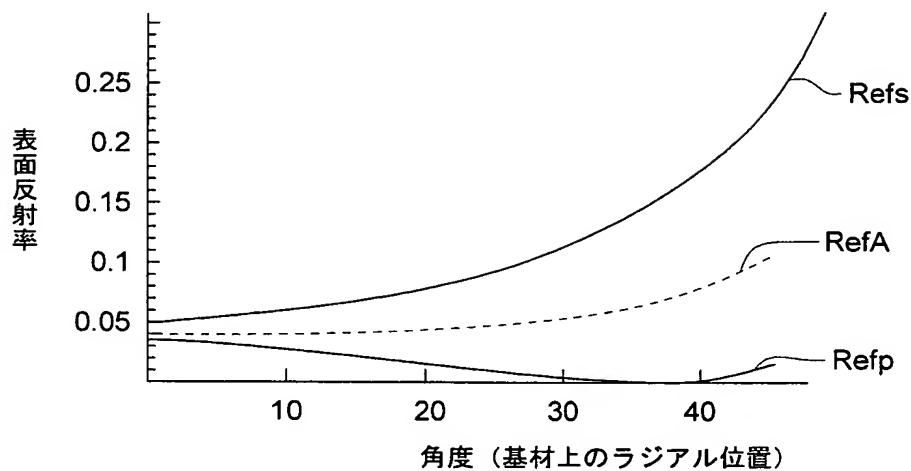
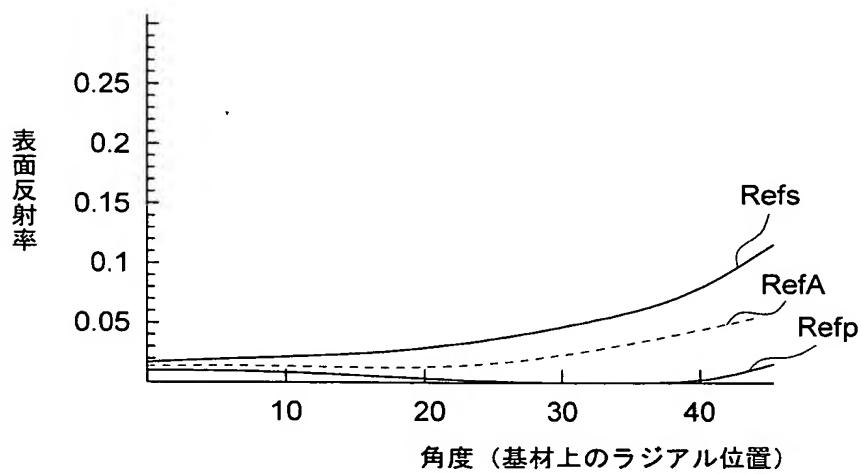


図 22

反射防止構造を設けた 回析格子 (3  $\mu$ )に反射防止構造のついたレンズ  
非クラスター部 面積比 70%



## 図 23

```

n2:=1.5      (*屈折率*)
s:=0.7      (*非クラスター部面積比*)
n1:=n2* √ s
β :=20      (*回析格子面の角度*)
ψ:=(orgψ+β)*3.141592 / 180 ----- (11)
x :=ArcSin [ Sin[ψ] / n1 ] (*屈折率*) -- (12)
Refp:= (Tan[ψ-x])2 ----- (13)
Refs:= (Sin[ψ-x])2 ----- (14)
RefA:= (Refp+Refs) / 2 ----- (15)

```

S11

```

s:=1      (*通常*)
β :=0
Plot { {Refs, Refp, RefA} , {orgψ, 0.45} , PlotRange→ {0, 0.3} ,

```

S12

```

s:=1      (*回析格子付きレンズ ピッチ20μ *)
β :=3
Plot { {Refs, Refp, RefA} , {orgψ, 0.45} , PlotRange→ {0, 0.3} ,

```

S13

```

s:=1      (*回析格子付きレンズ ピッチ3μ *)
β :=20
Plot { {Refs, Refp, RefA} , {orgψ, 0.45} , PlotRange→ {0, 0.3} ,

```

S14

```

s:=0.7      (*回析格子付きレンズ ピッチ3μ 表面反射防止構造付き*)
β :=20
Plot { {Refs, Refp, RefA} , {orgψ, 0.45} , PlotRange→ {0, 0.3} ,

```

S15

図 24

第2回 第1章 “電子顕微鏡による非球面加工”

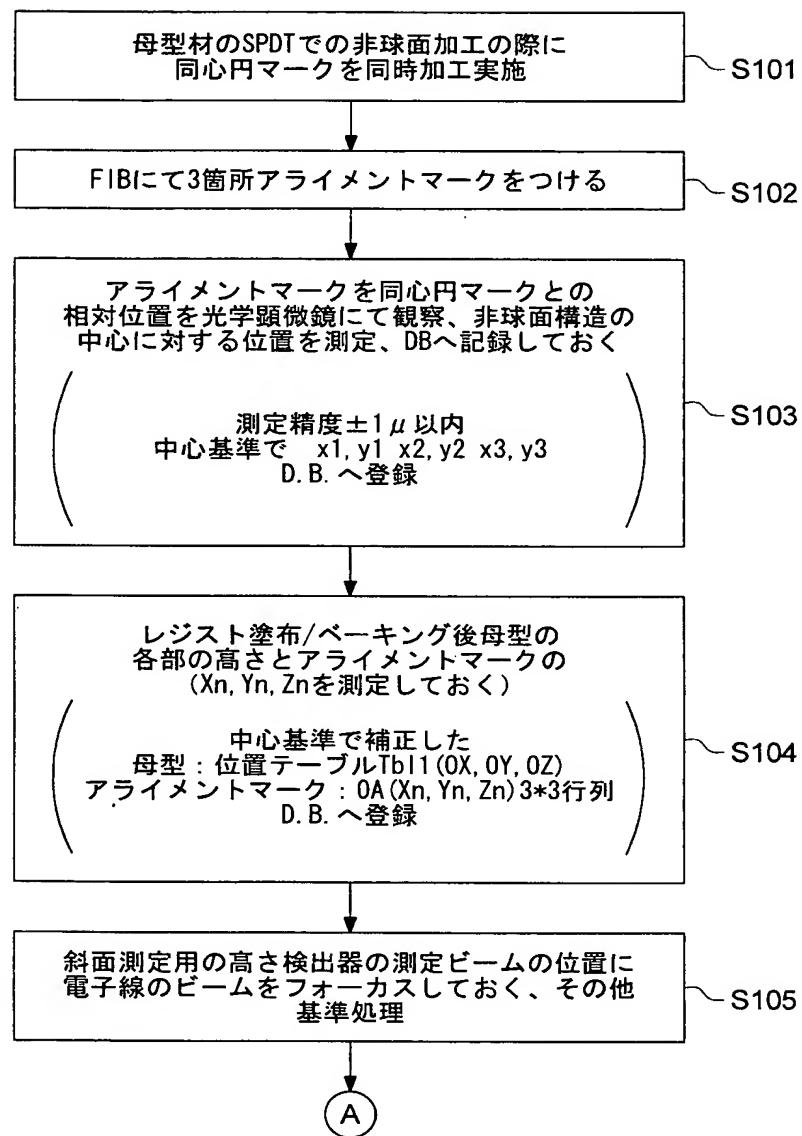
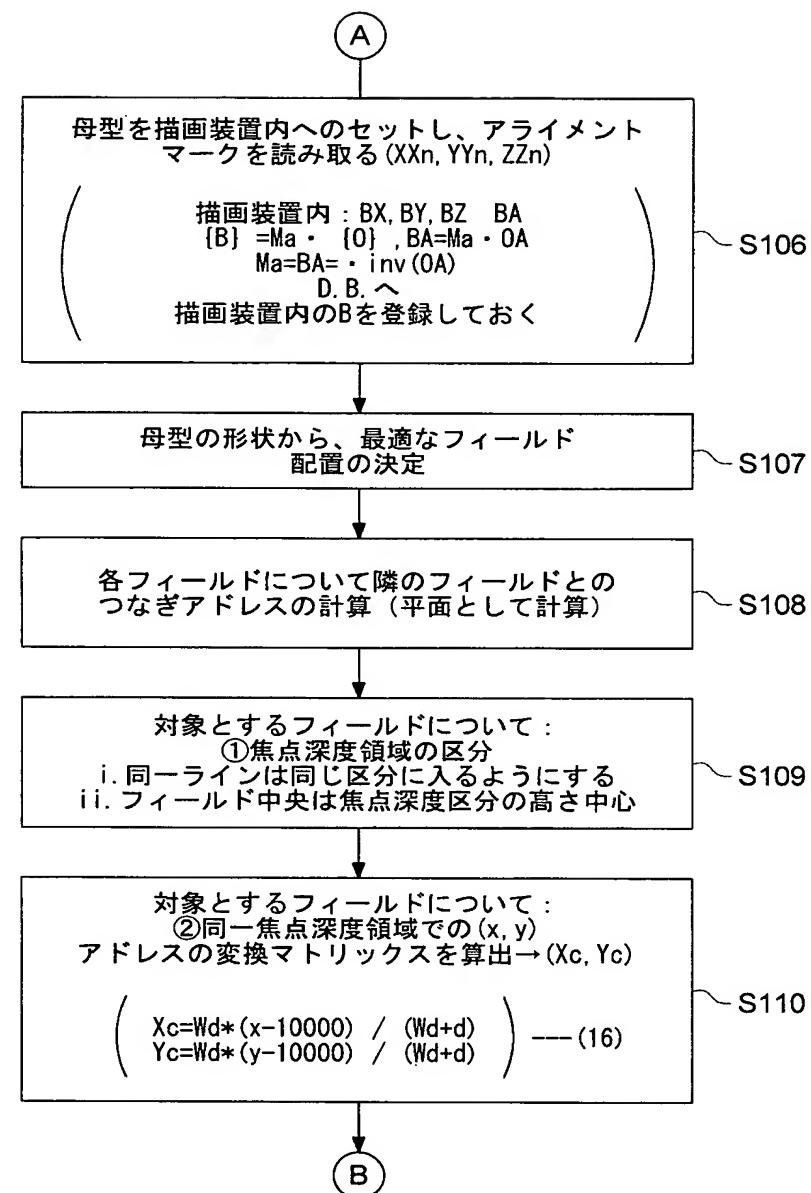


図 25

特許出願用電子回路



四 26

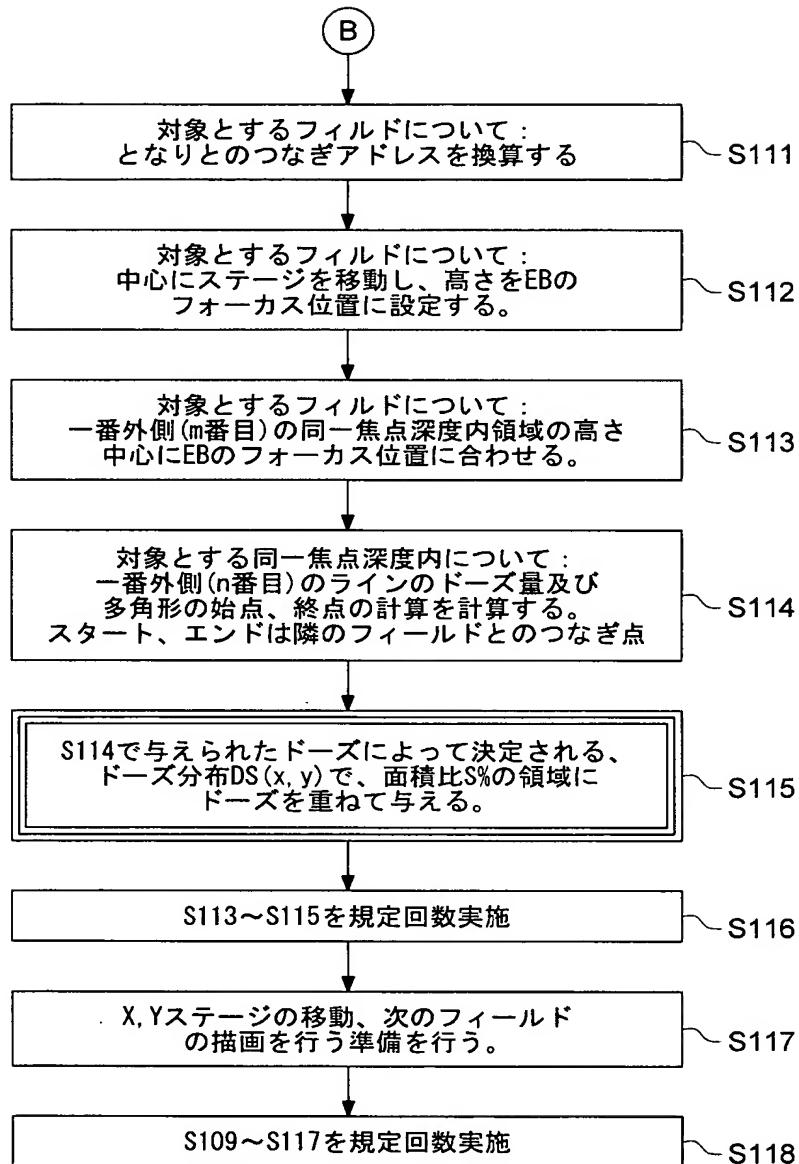


図 27 (A)

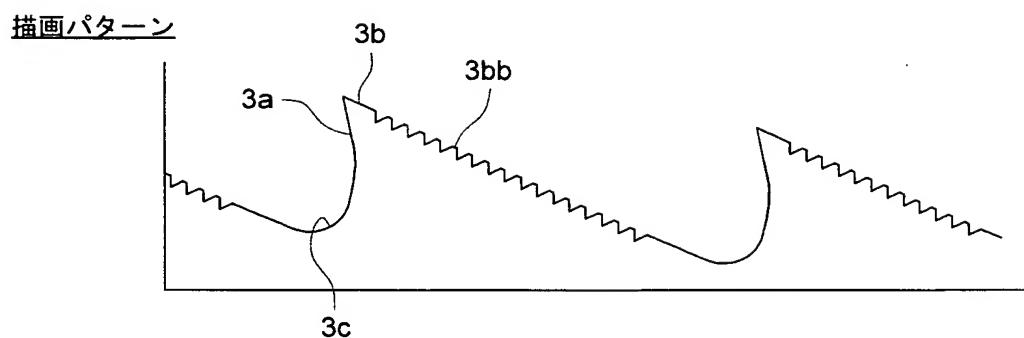


図 27 (B)

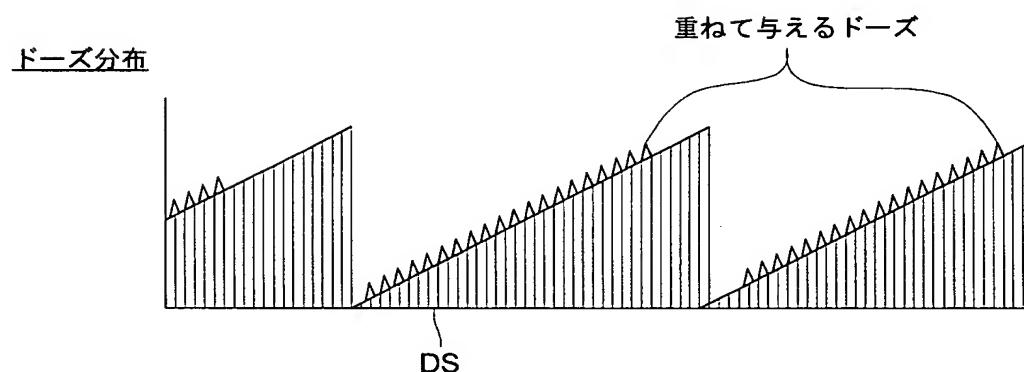


図 28 (A)

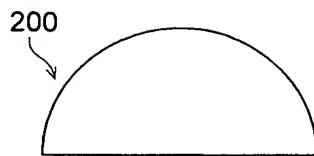


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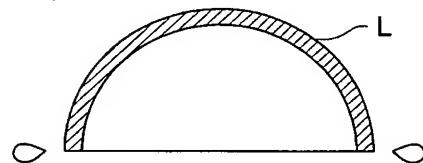


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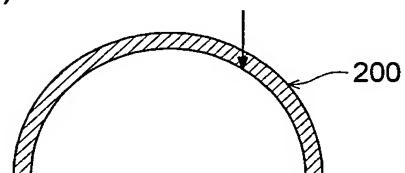


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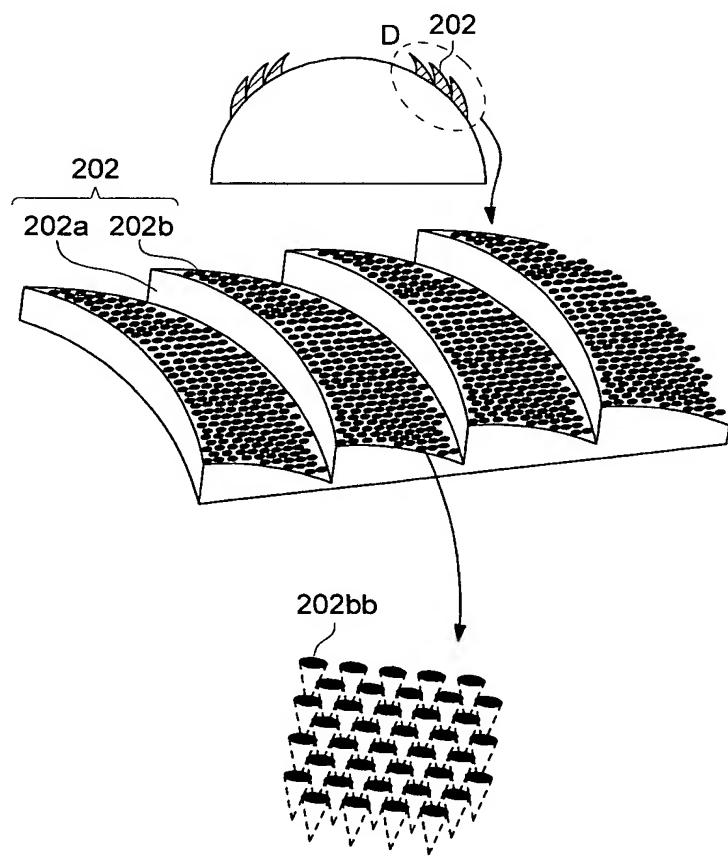


図 29 (A)

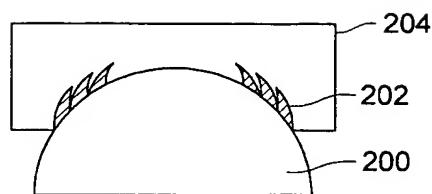


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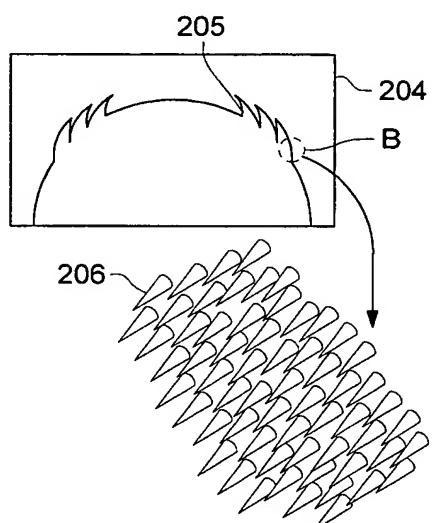


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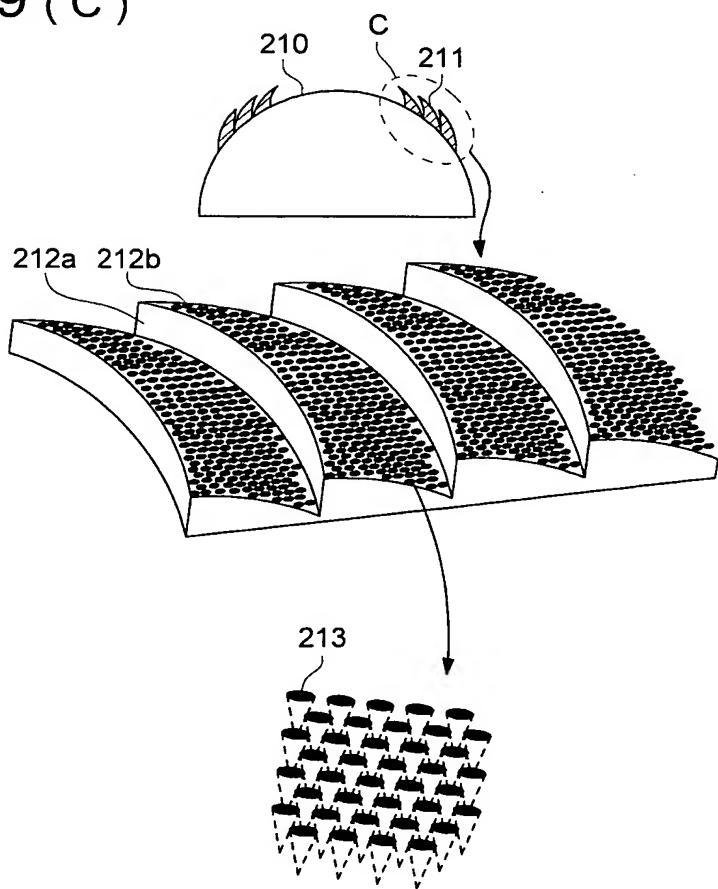


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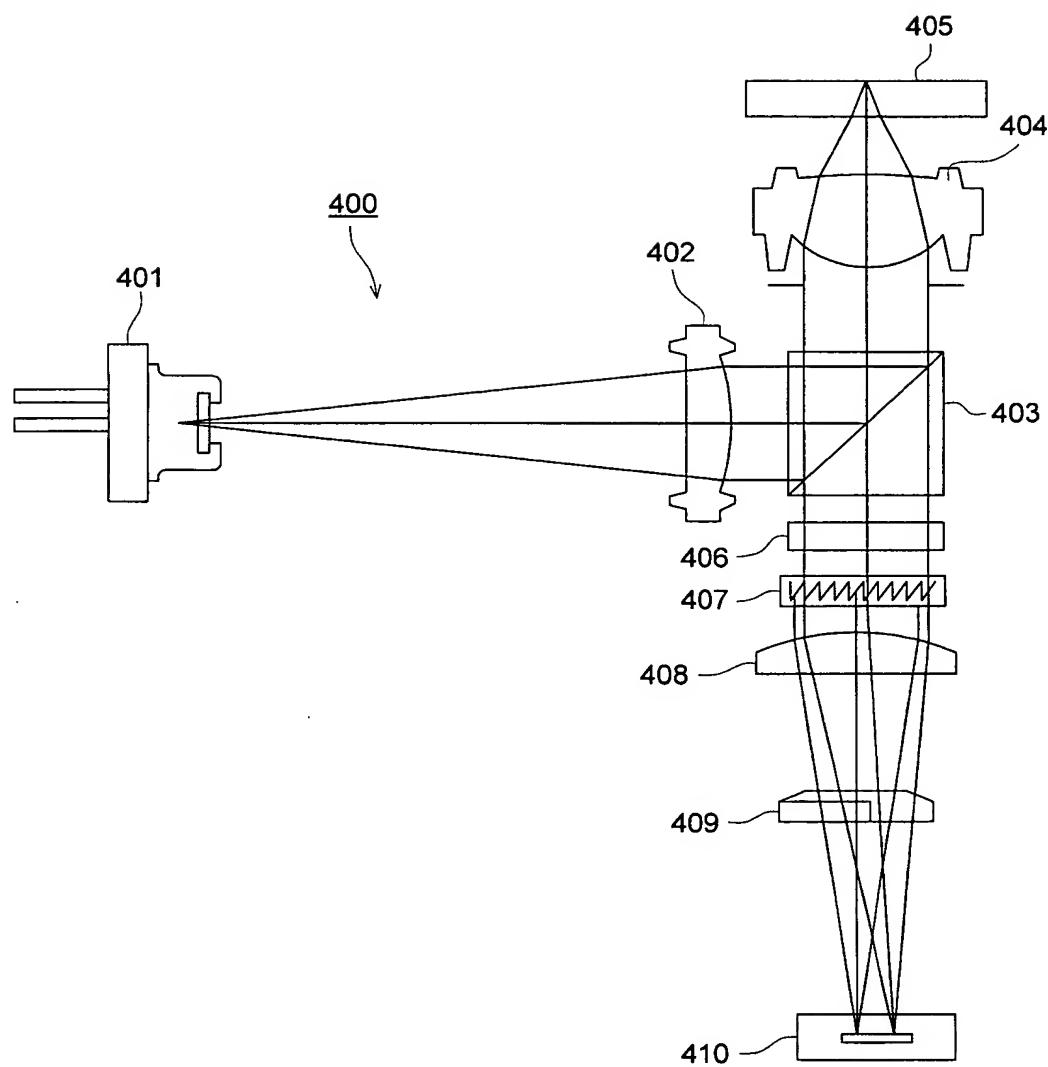


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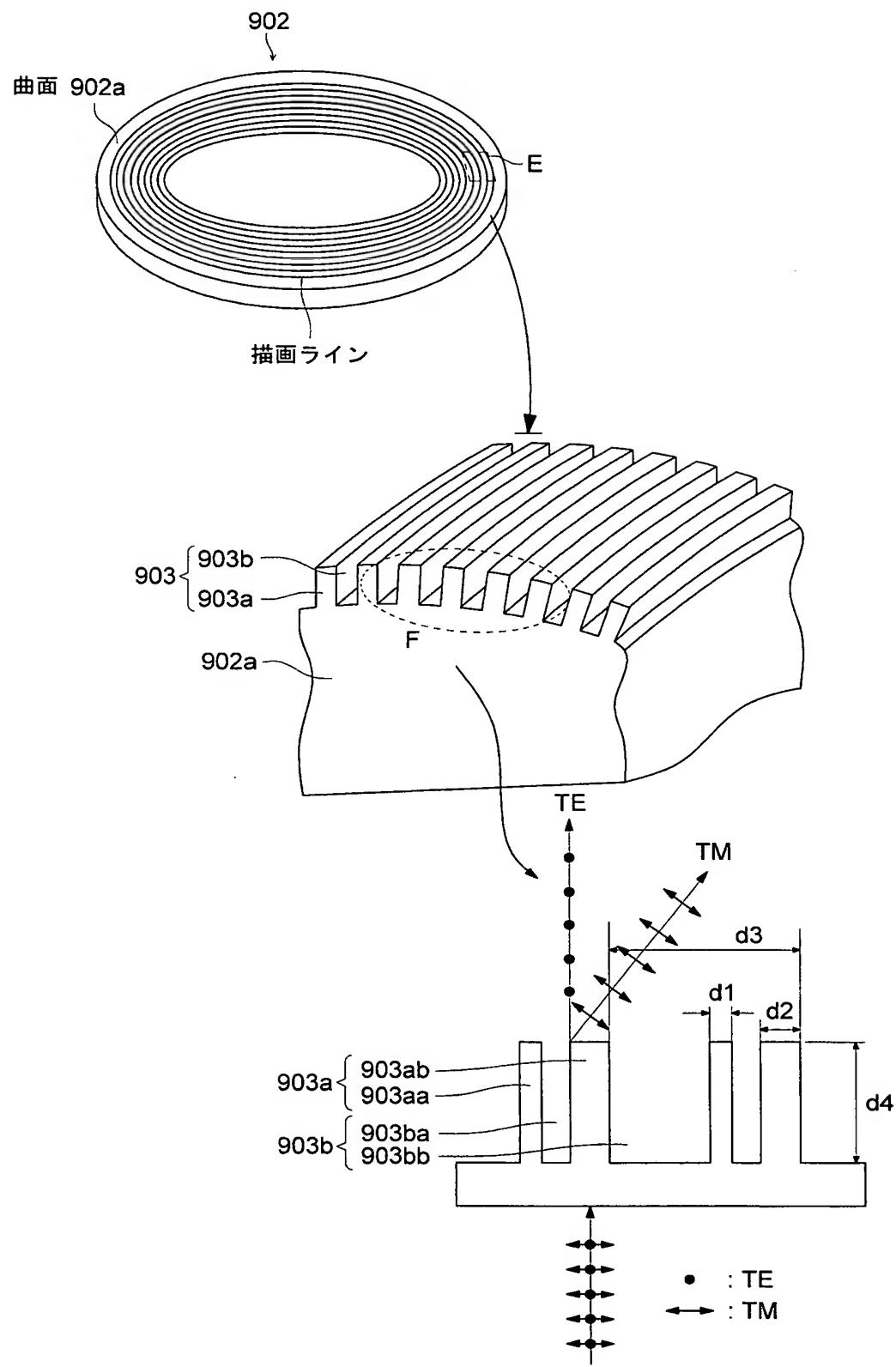


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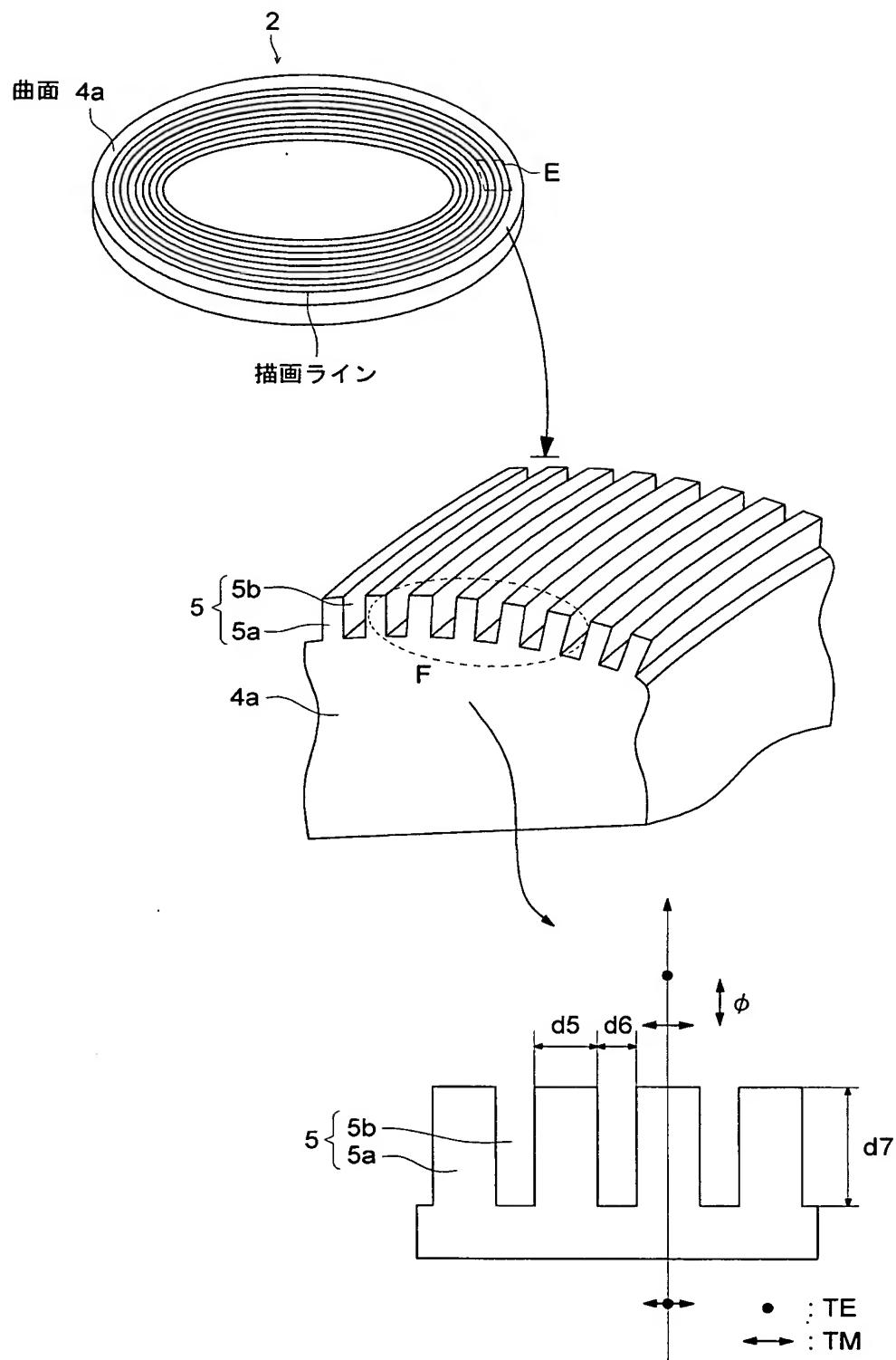


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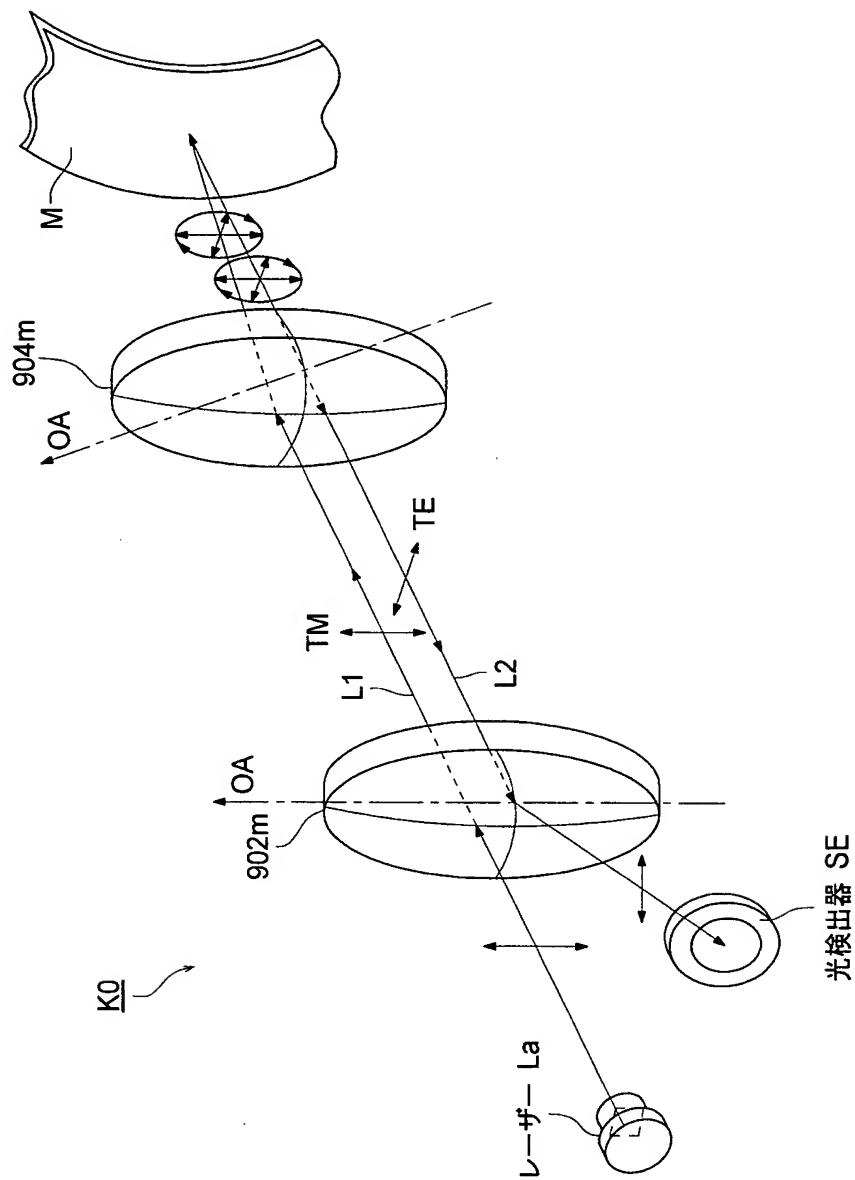


図 34 (A)

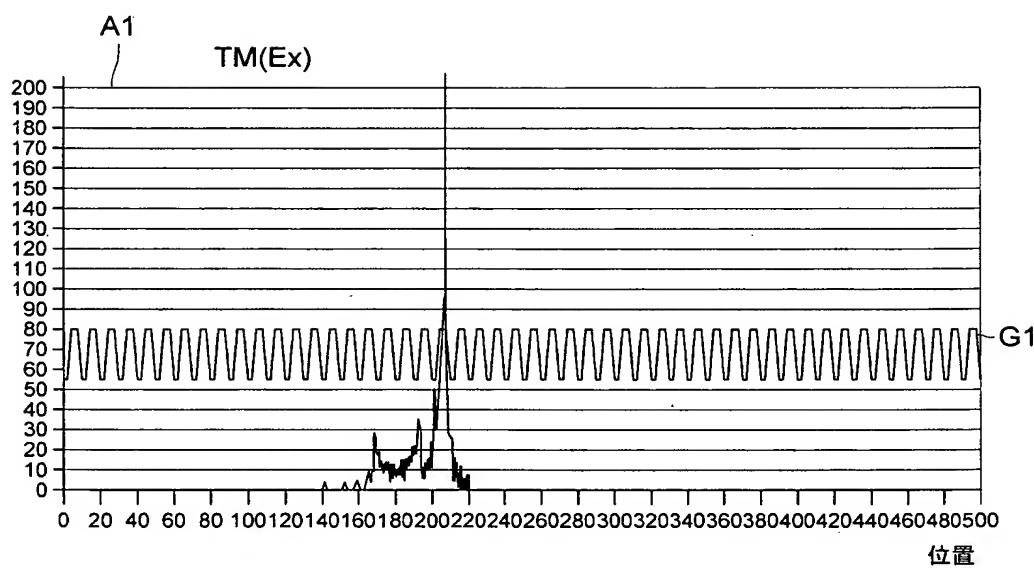


図 34 (B)

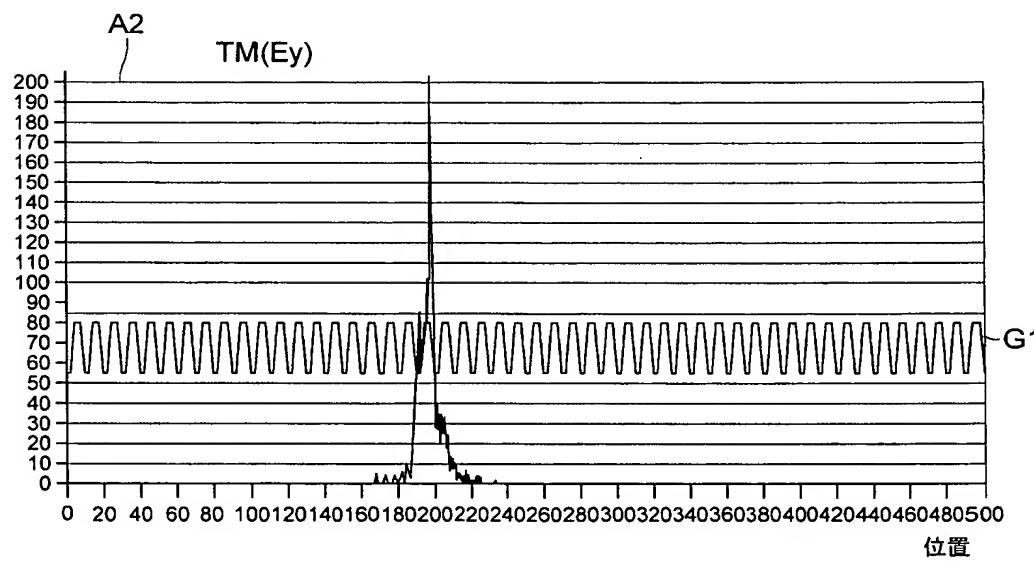


図 35 ( A )

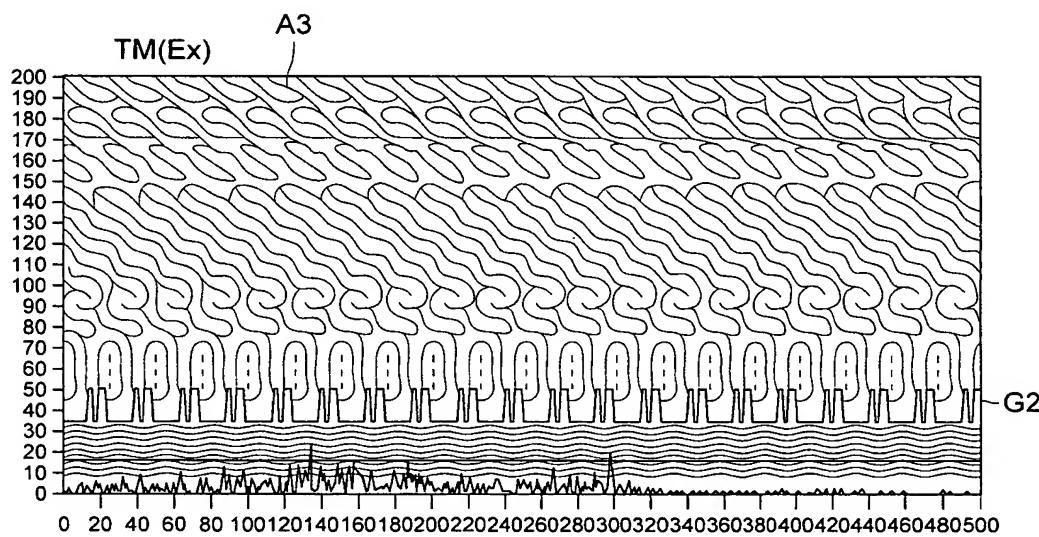


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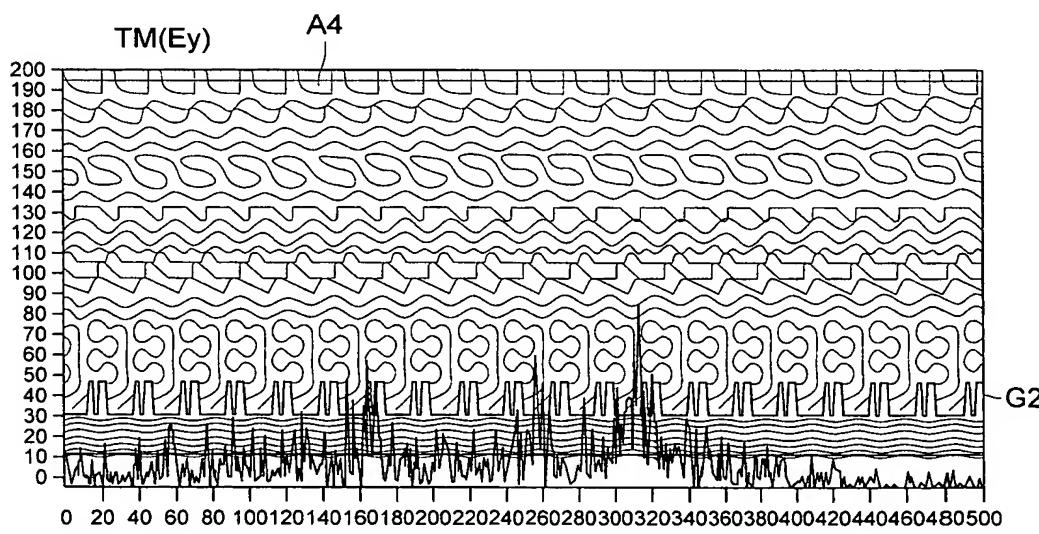


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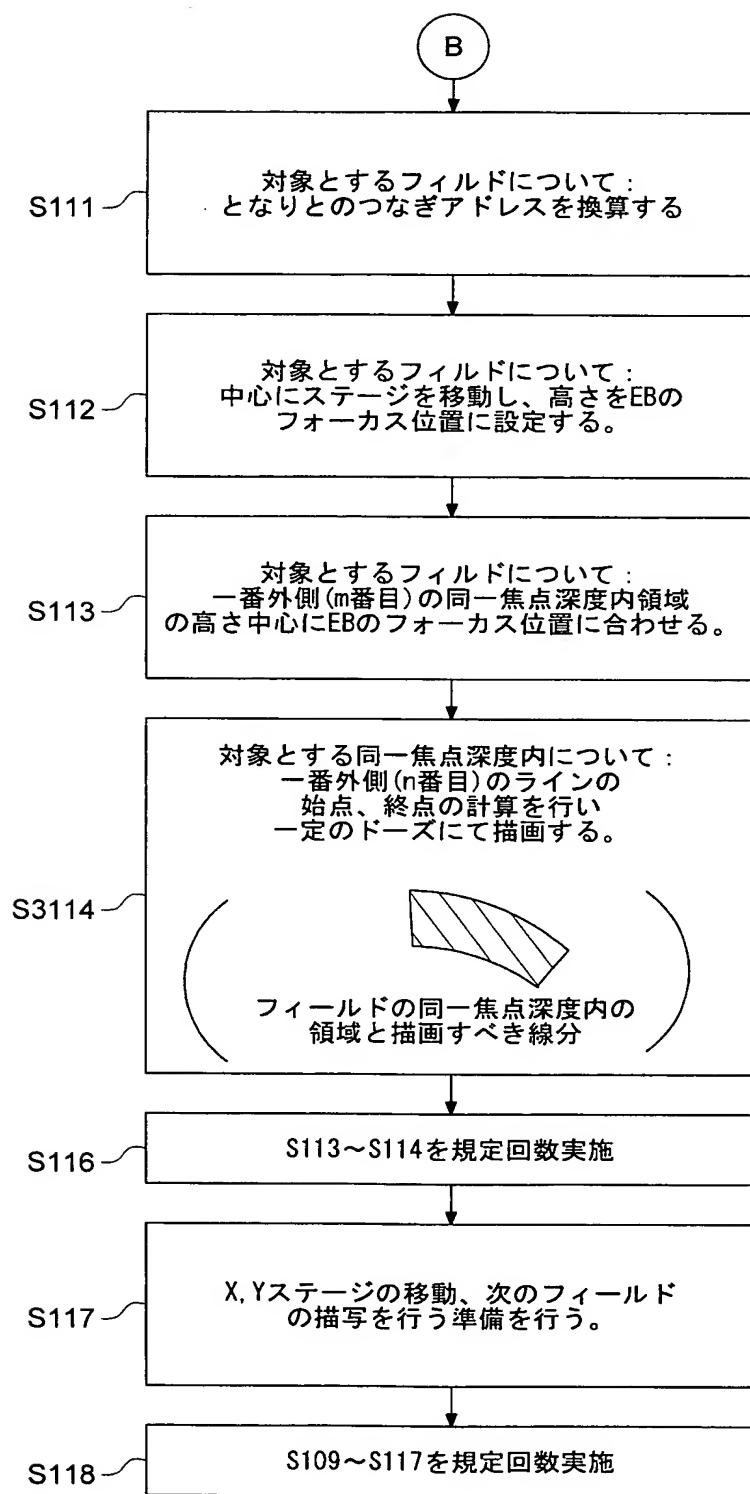


図 37 (A)

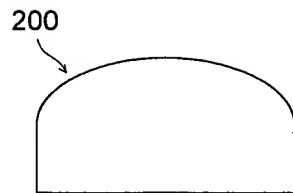


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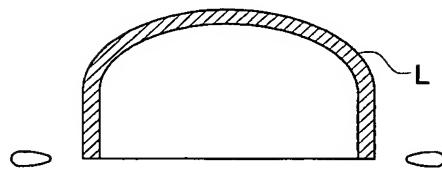


図 37 (C)

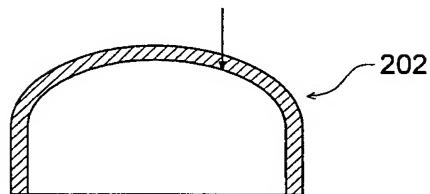


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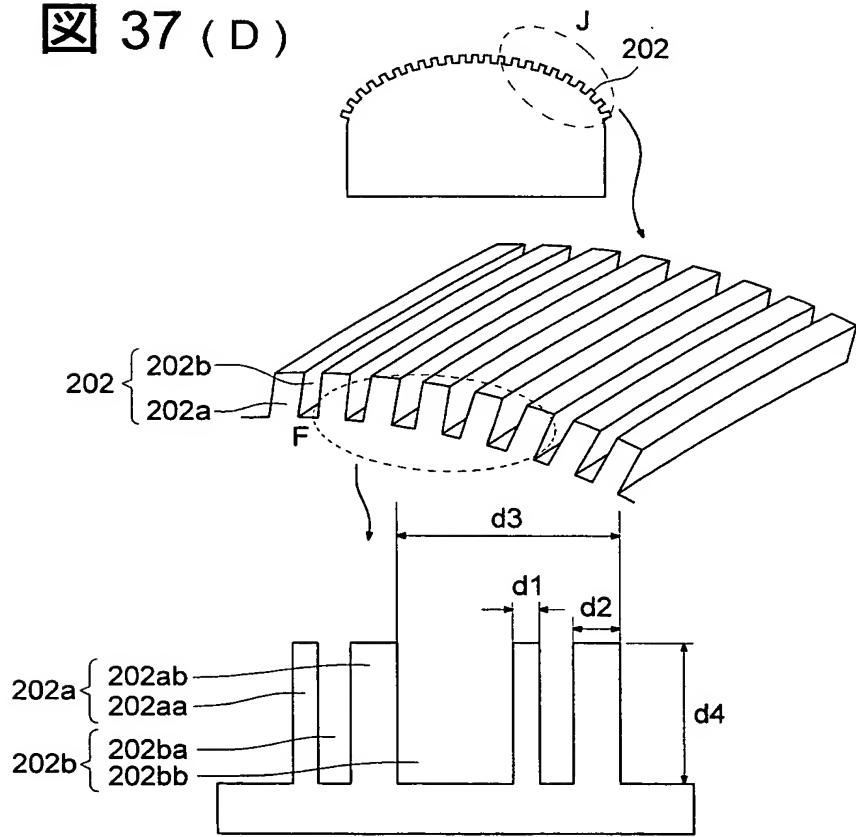


図 38 ( A )

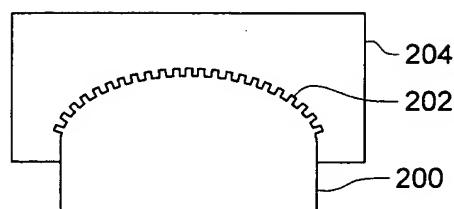


図 38 ( B )

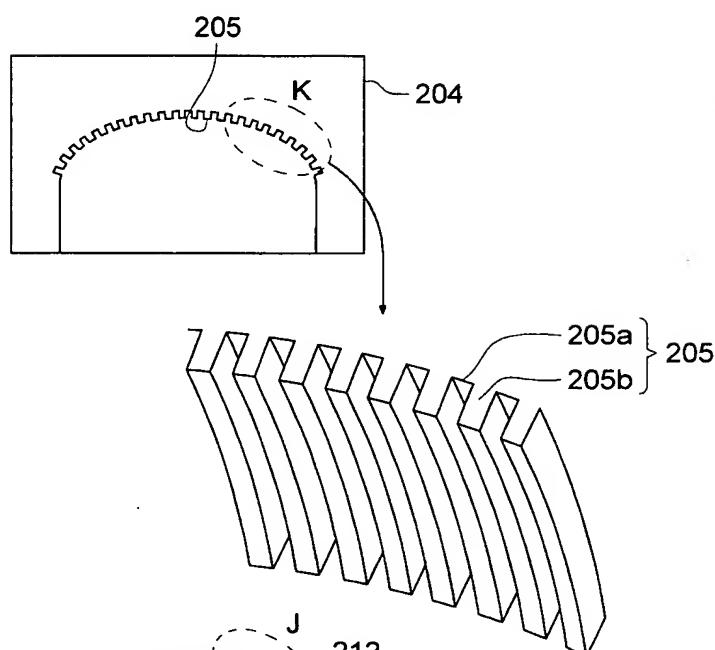


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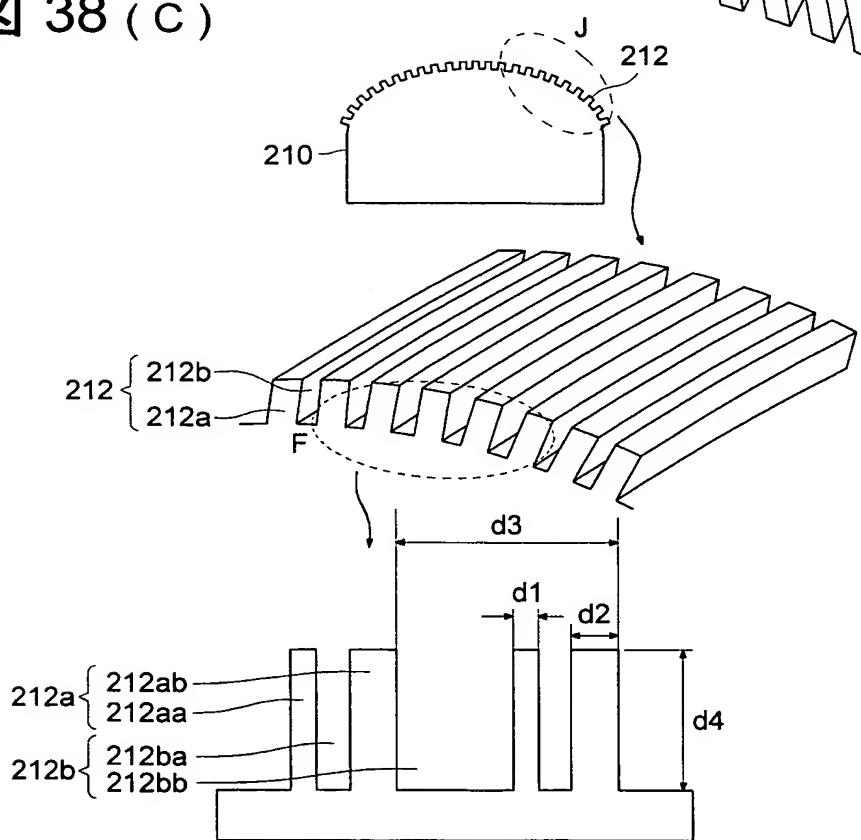


図 39 ( A )

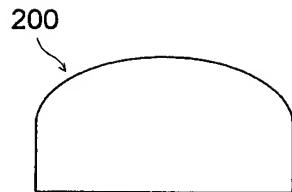


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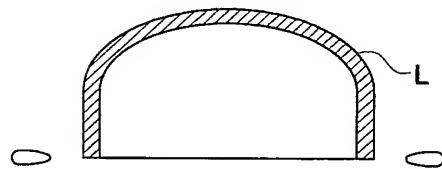


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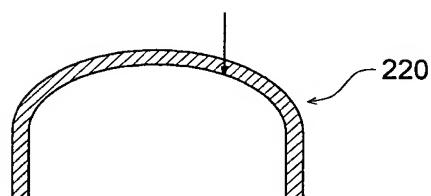


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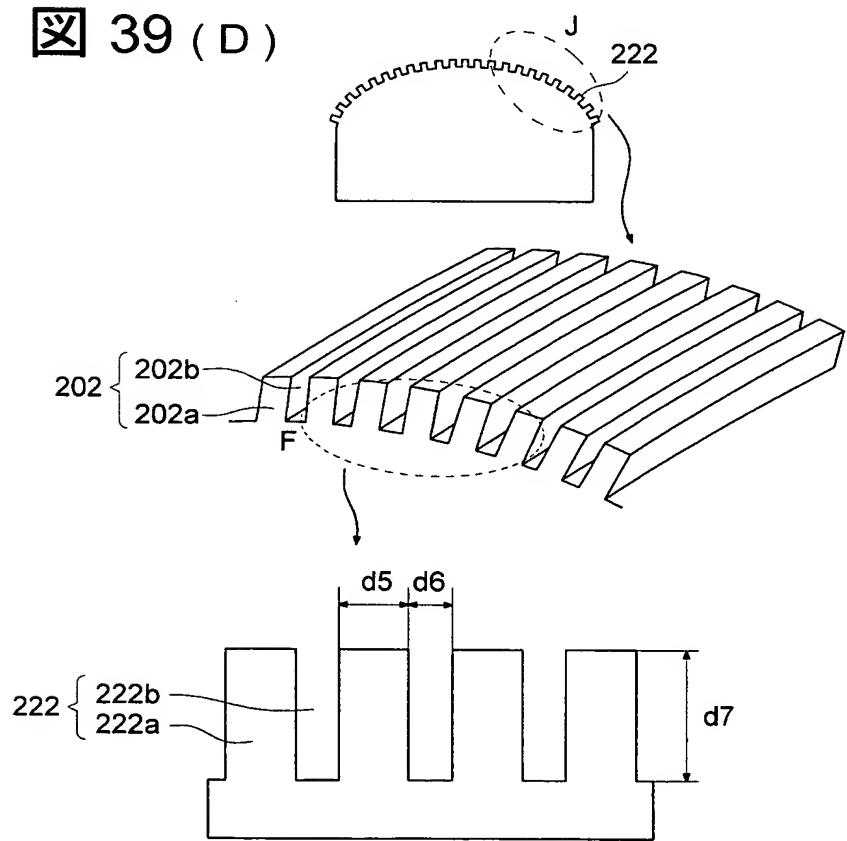


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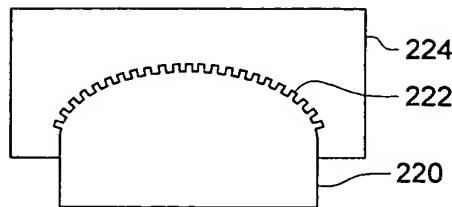


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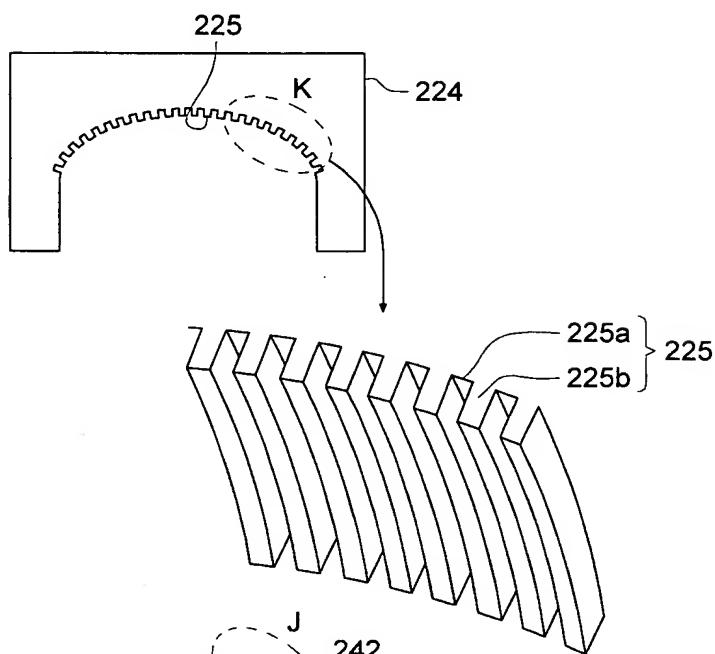


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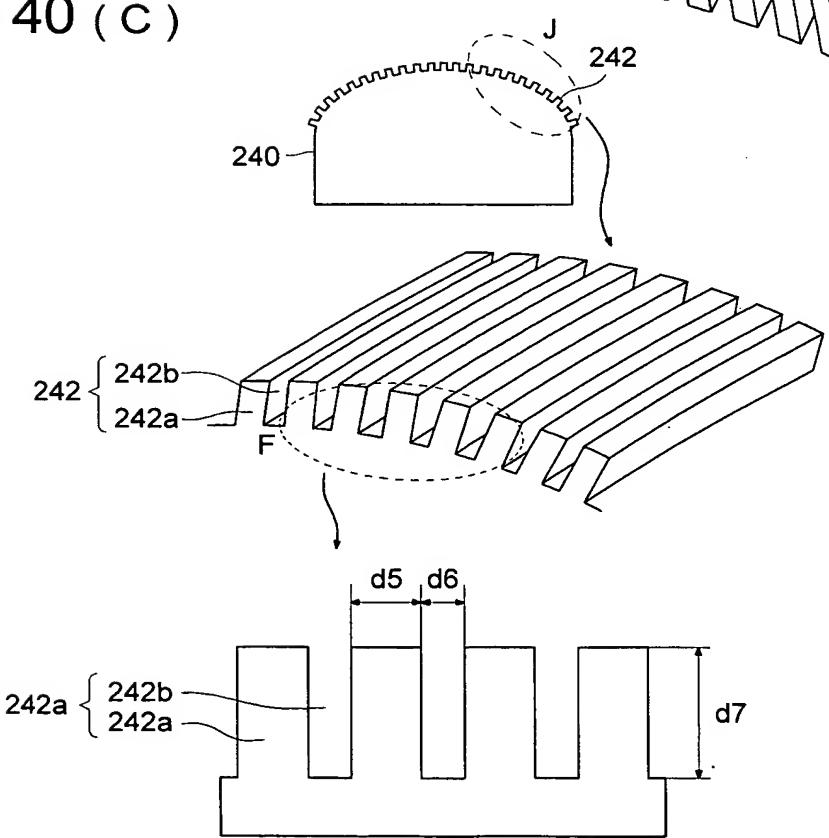


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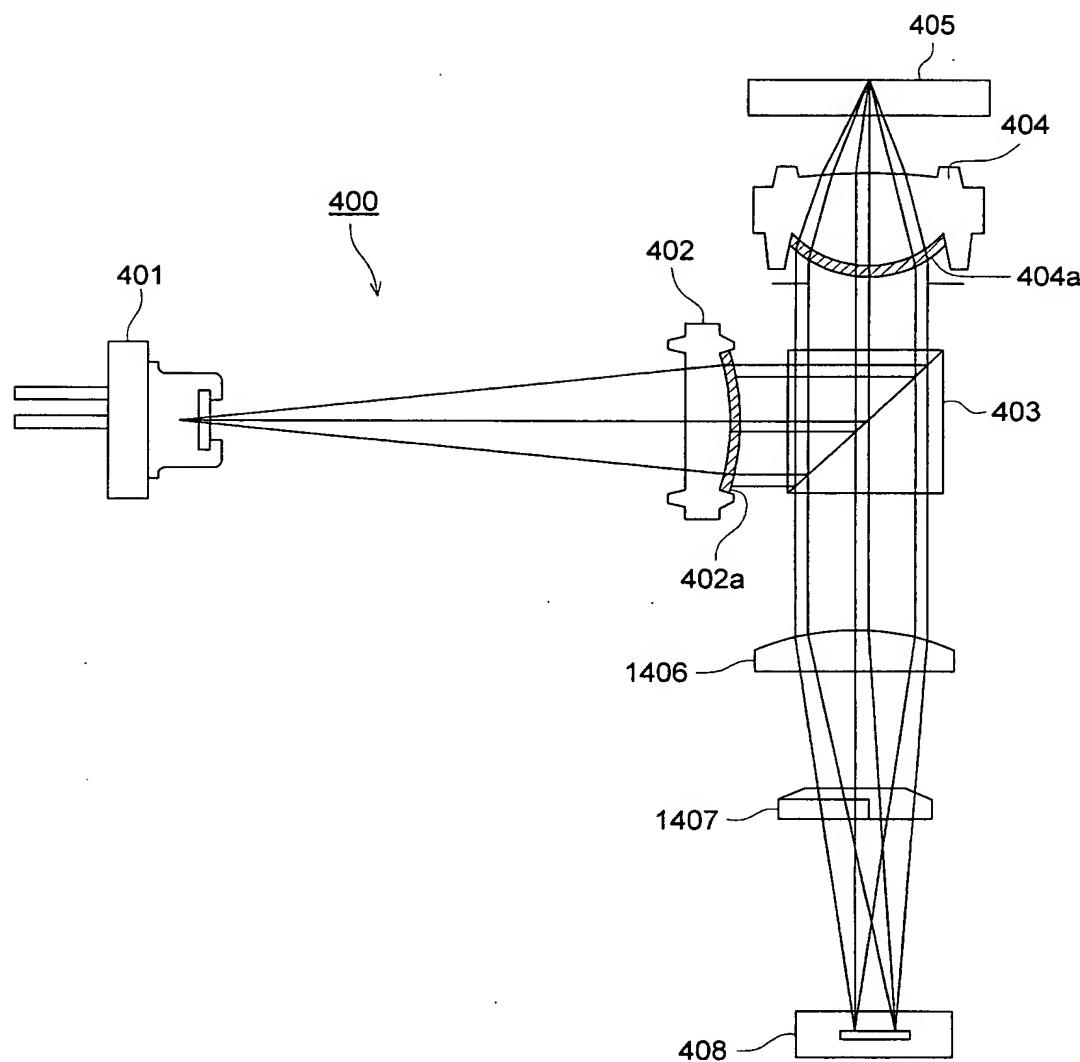


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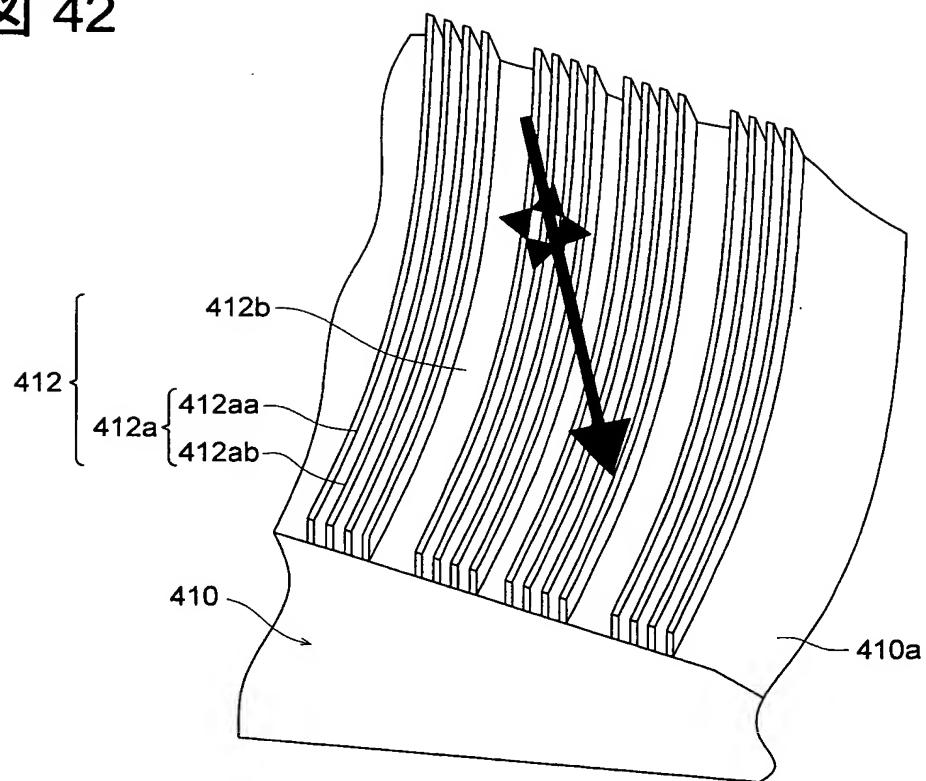


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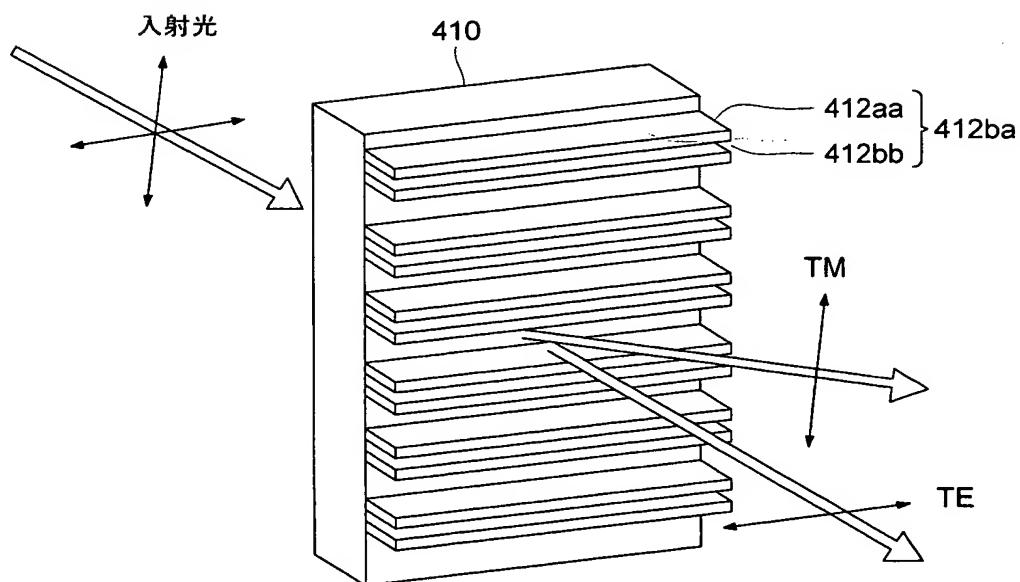


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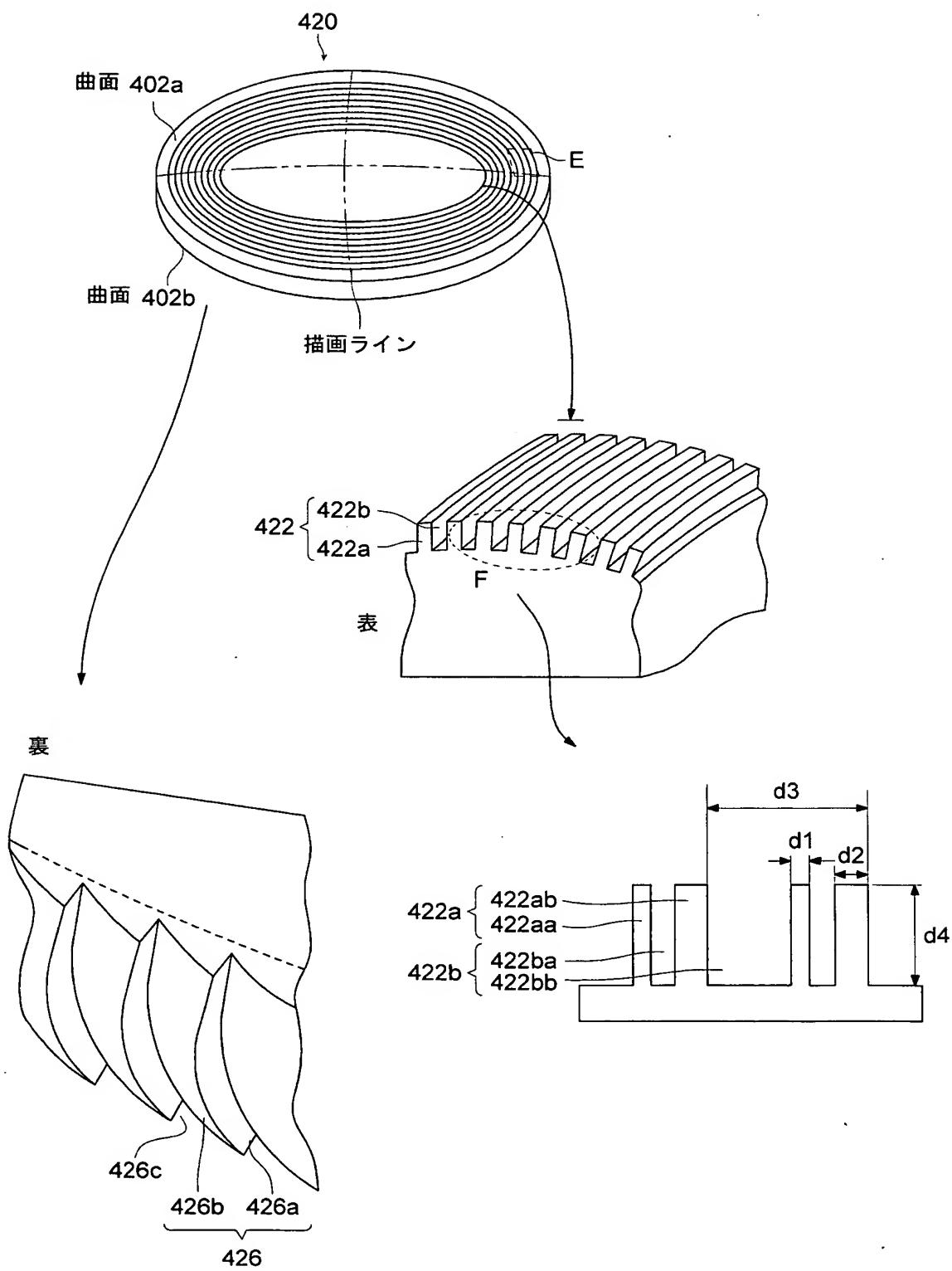


図 45 (A)

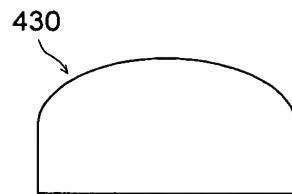


図 45 (B)

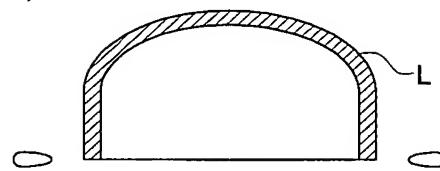


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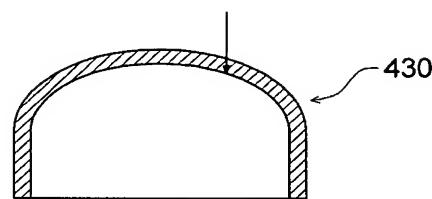


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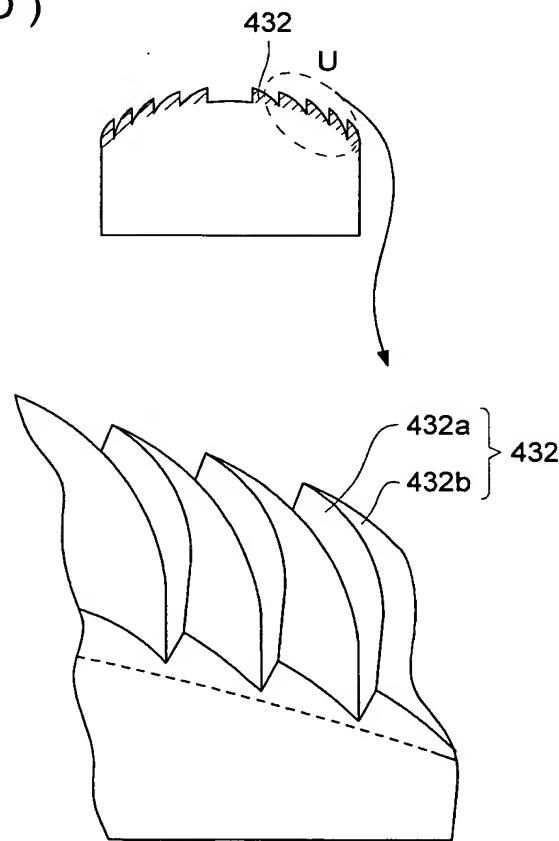


図 46 (A)

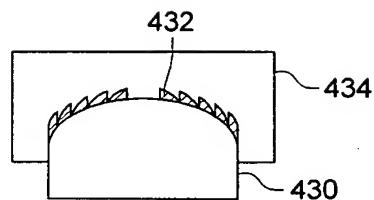


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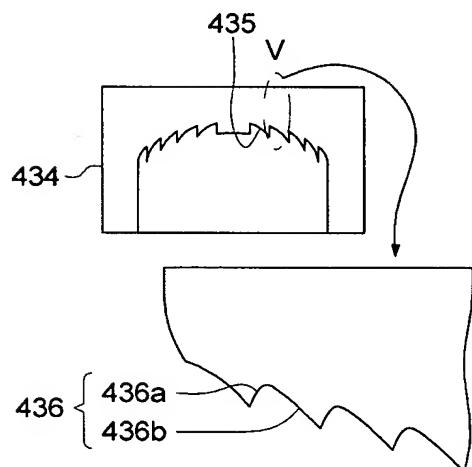


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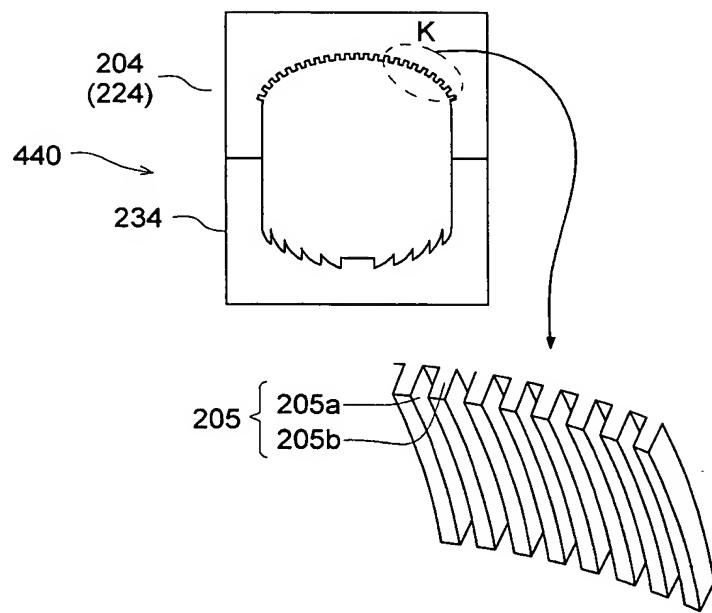


图 47

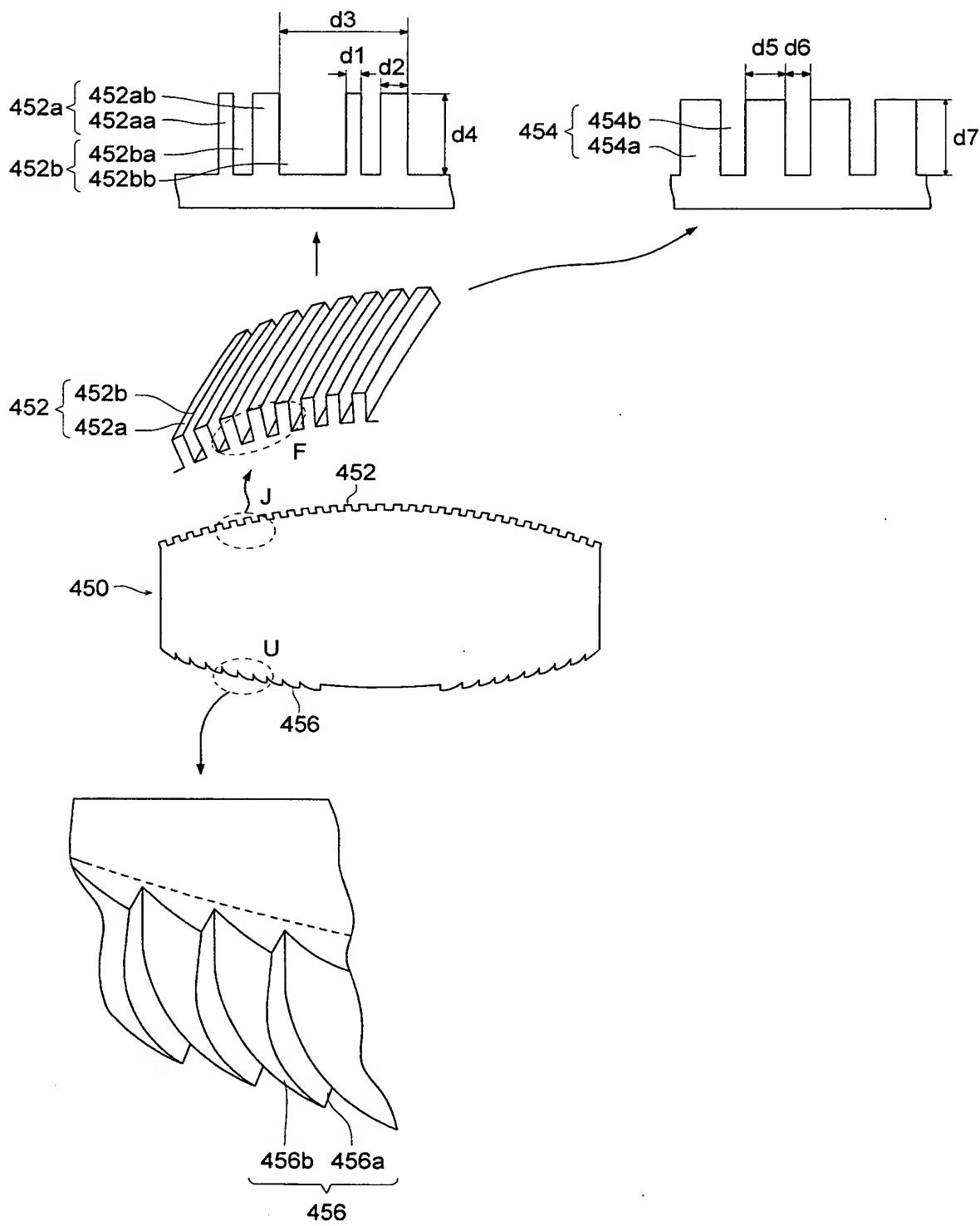


図 48

